

Silicon Photomultiplier (SiPM)

Status and Perspectives

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ICEPP, University of Tokyo

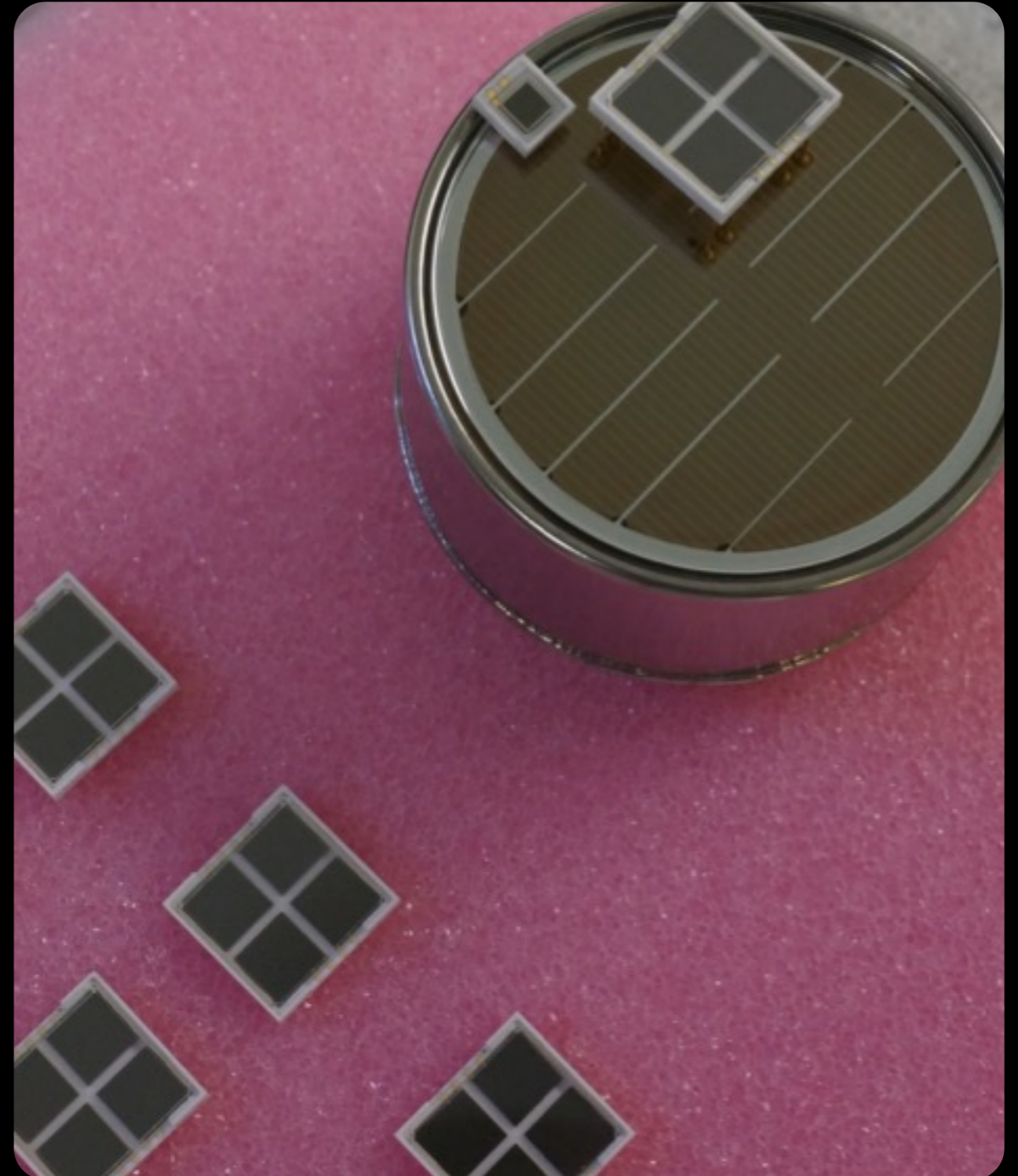
RD51 Academia-Industry Matching Event

Special Workshop on Photon Detection with MPGDs

June 10th, 2015 CERN

Contents

- Introduction
- Properties and Performance
- New Developments
- Application Examples
- Summary

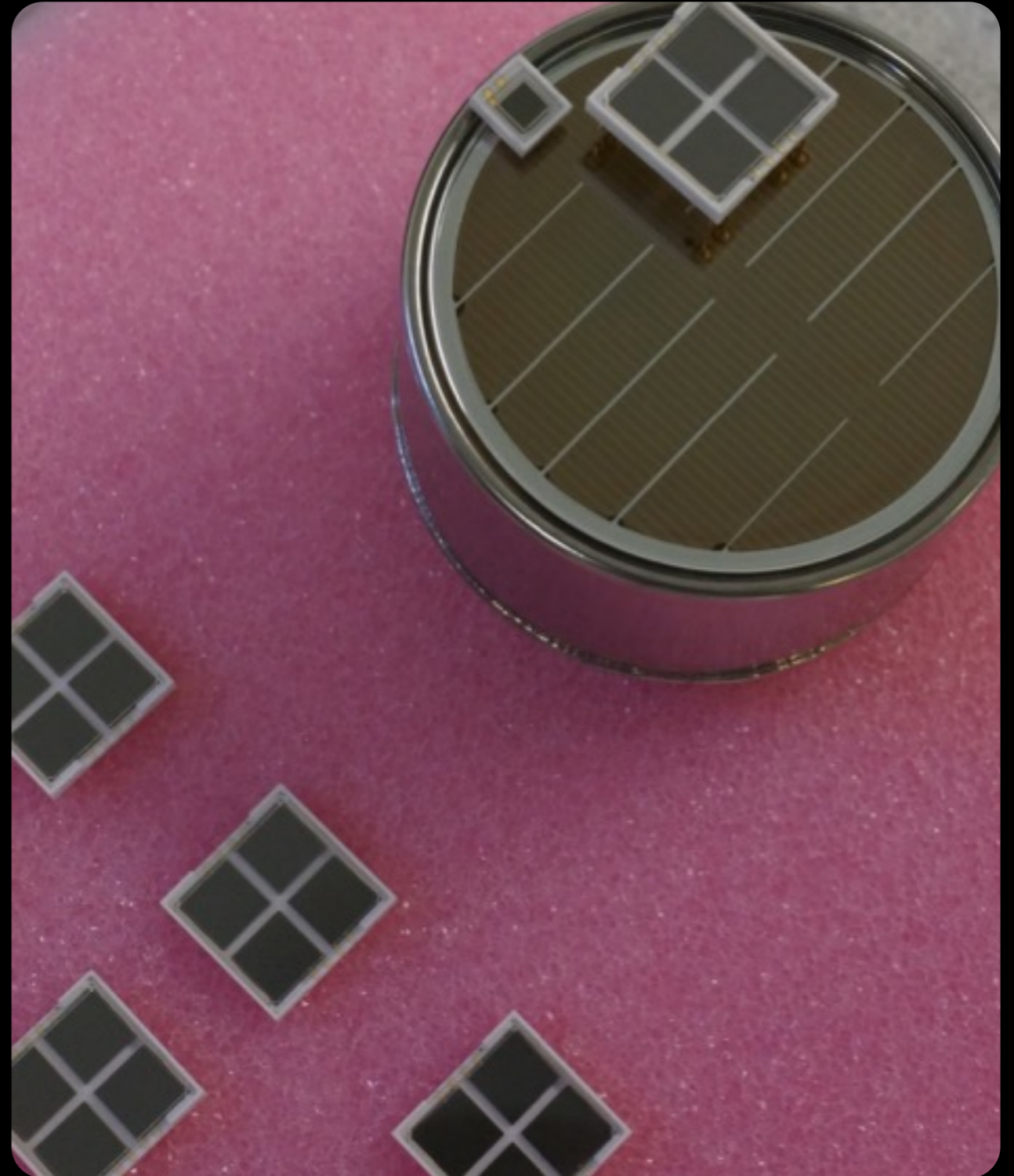


Caveats

- I apologise that I can't cover everything on SiPM in this talk because of the limited time.
- Topics selection is (very much) biased by my personal interests.

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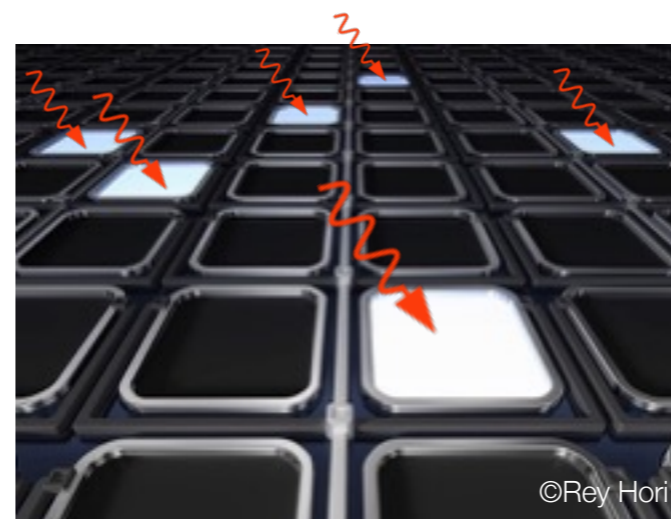
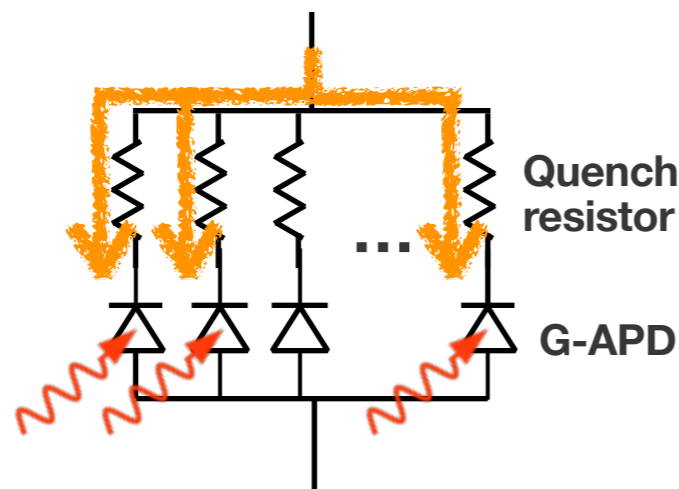
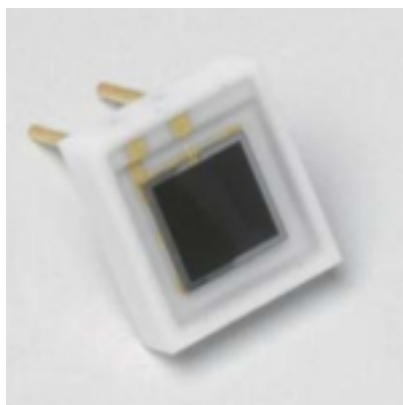
- **Introduction**
- Properties and Performance
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What Is Silicon Photomultiplier (SiPM)?

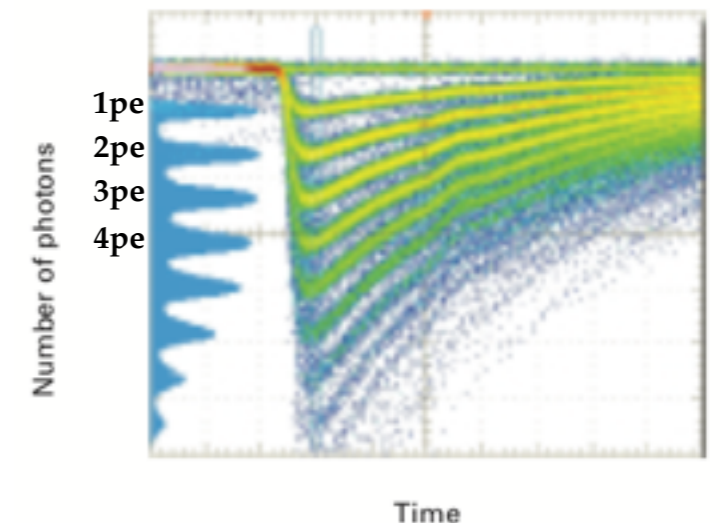
- **SiPM = Multi-pixelated Geiger-mode APD (G-APD).**
 - Tiny G-APD cells are connected in parallel together with resistor for self-quenching of avalanche
 - Each G-APD cell is a “binary” device. The same charge from each photon trigger.
 - SiPM output is a sum of signals from triggered G-APD cells.
- **SiPM output is proportional to # of impinging photons**
 - SiPM = “analogue” device.
- **Pioneering works by Russian institutes in late 80ies (Golovin, Dolgoshein, Sadygov)**

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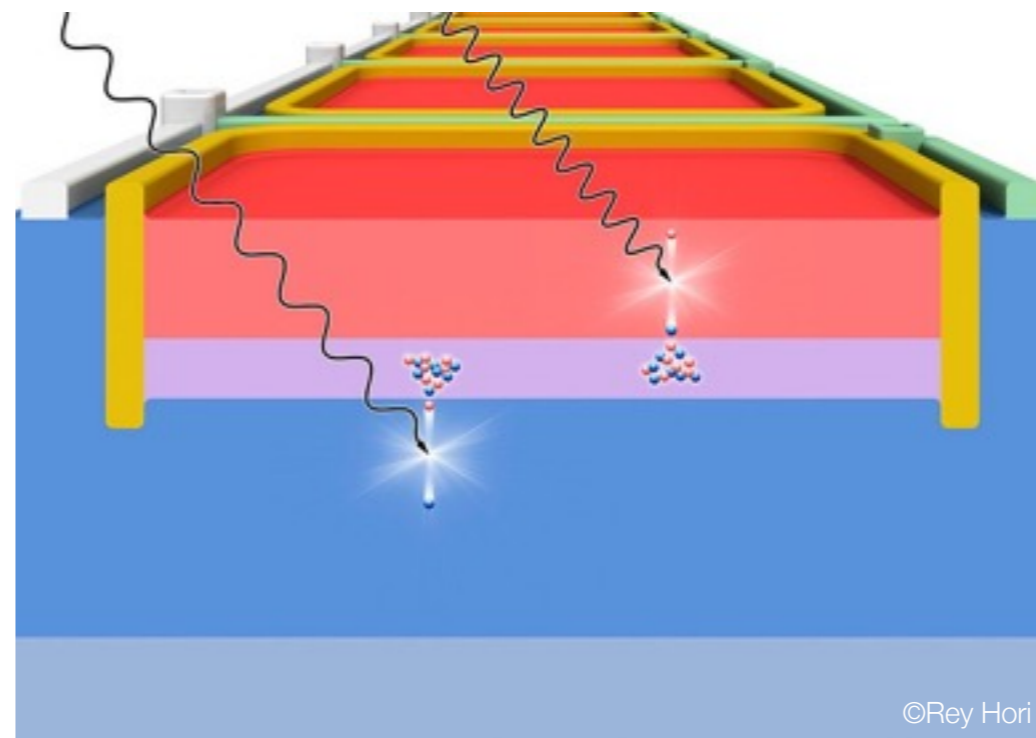
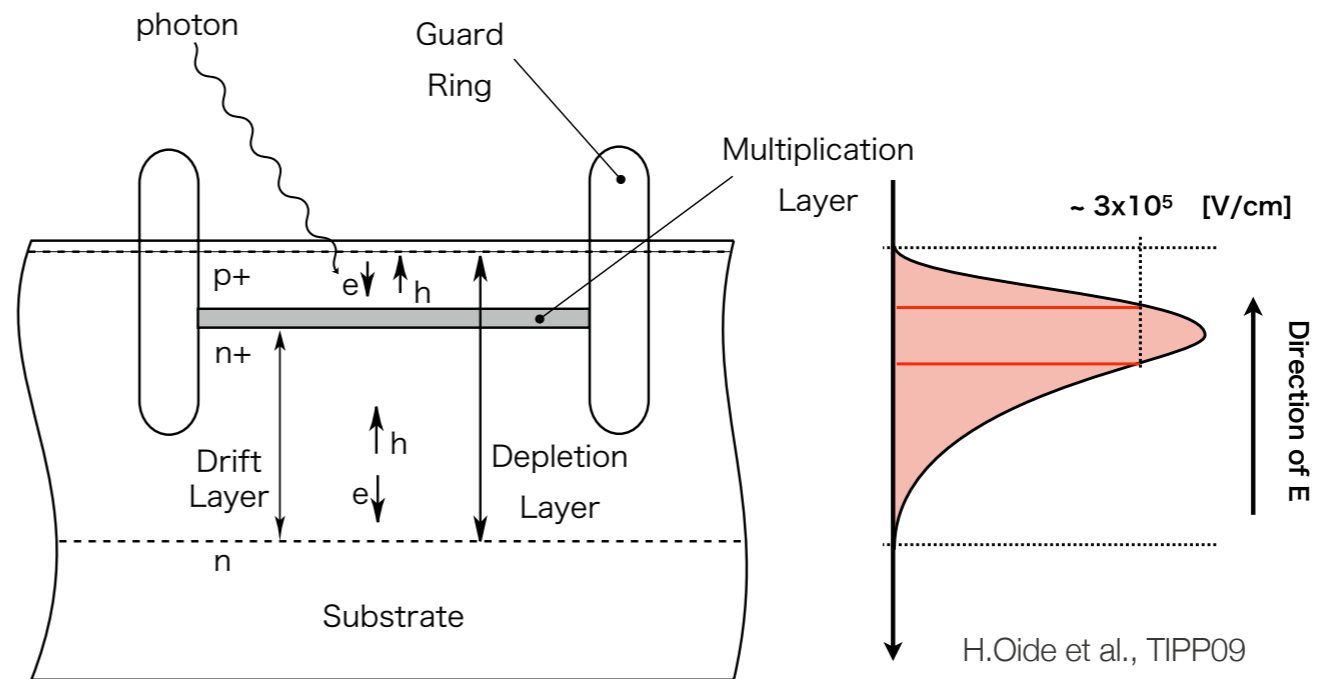
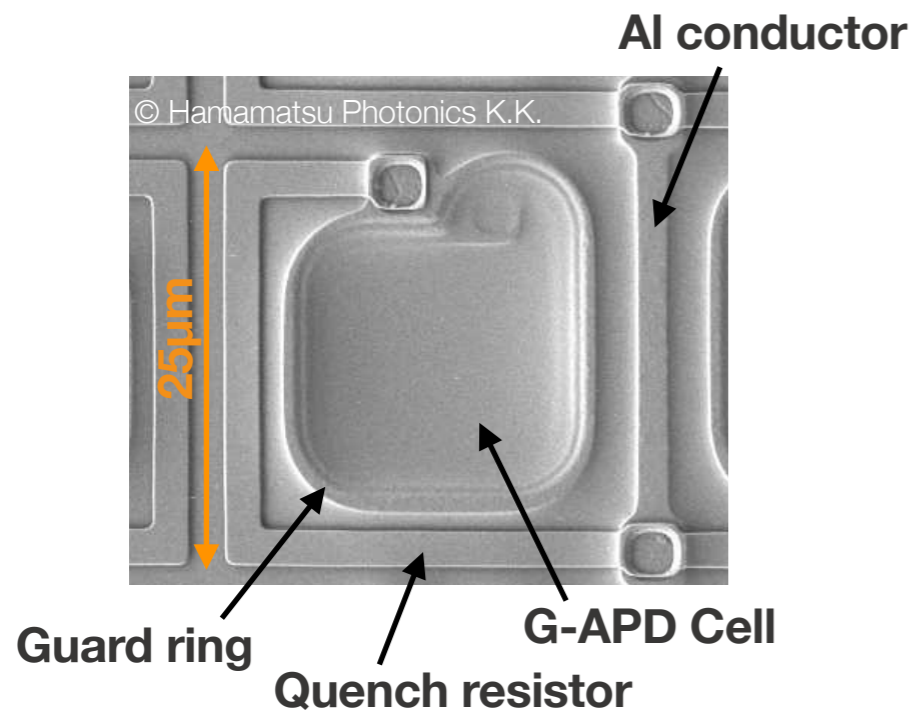
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Time

Closer Look at Cell



SiPM: Basic Parameters

| | |
|-----------------------------------|-----------------------------------|
| Sensor size (single) | 1×1 - 6×6mm ² |
| Cell size (cell pitch) | 10 - 100μm |
| Quench resistor | 10k - 10MΩ |
| Internal gain | 10 ⁵ - 10 ⁶ |
| Photon detection efficiency (PDE) | 20 - 50% |
| Time resolution (single photon) | O(100ps) (FWHM) |
| Dark noise rate | 50k - 1M Hz/mm ² |
| Bias voltage | 20 - 70 V |

Advantages of SiPM

- High photon detection efficiency
- High internal gain
- Insensitive to B-field
- Good single photoelectron resolution
- Fast (good timing resolution)
- Low bias voltage (<100V)
- Low power consumption
- Compact
- Low cost

Weak Points of SiPM

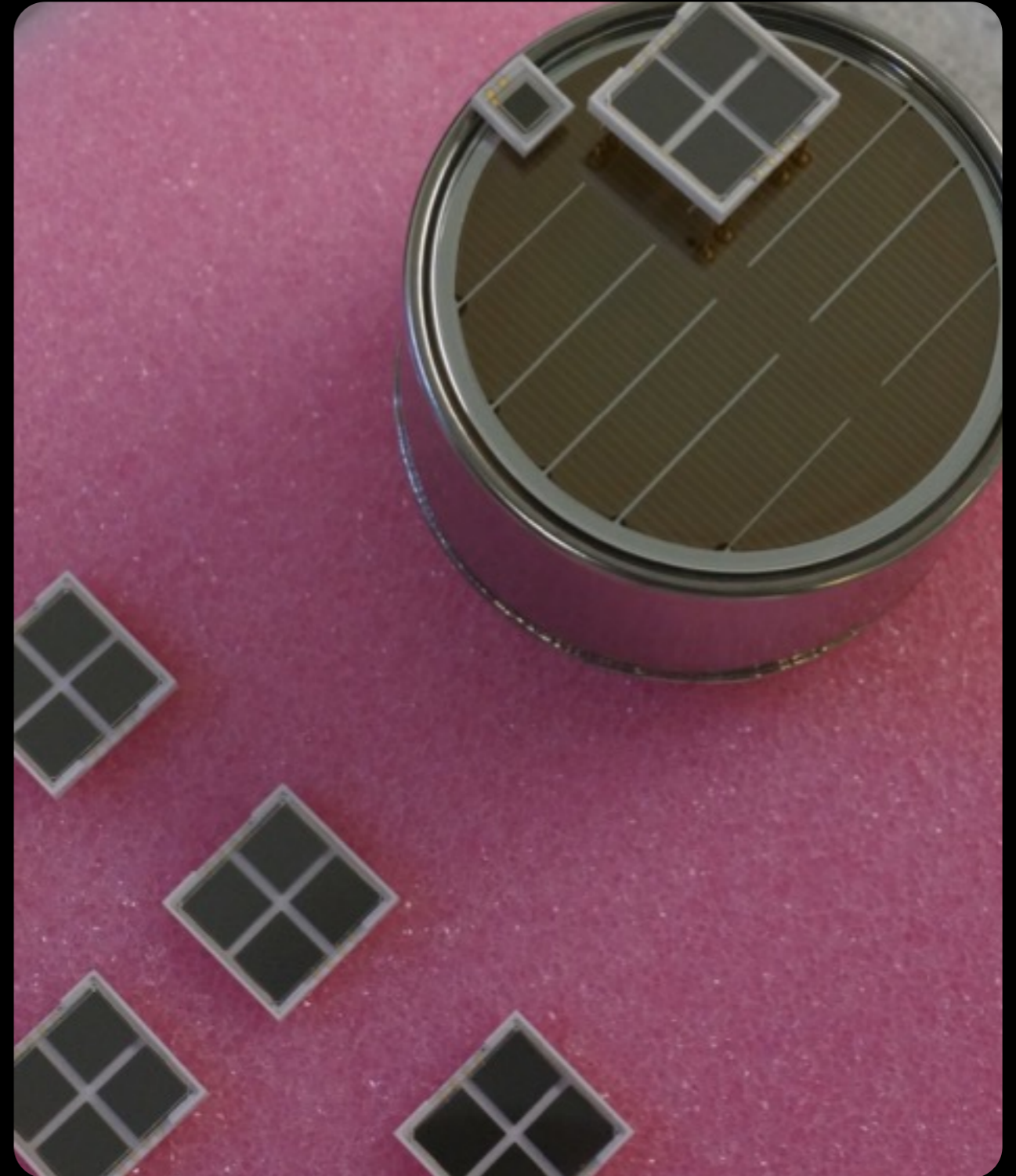
- Large sensor area is difficult.
- Temperature dependence
- Noise (dark noise + correlated noise)
- Radiation hardness
- Saturation for a large number of incoming photons

SiPMs from over The World



Contents

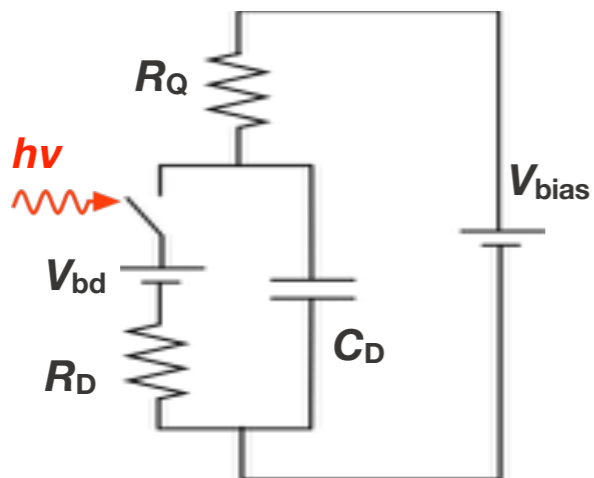
- Introduction
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Pulse Shape

- SiPM cell operation cycle (simplified model)

- ① Photo-generation of carrier → avalanche (switch ON)
- ② Self-quenching (switch OFF)
- ③ Re-charge cell



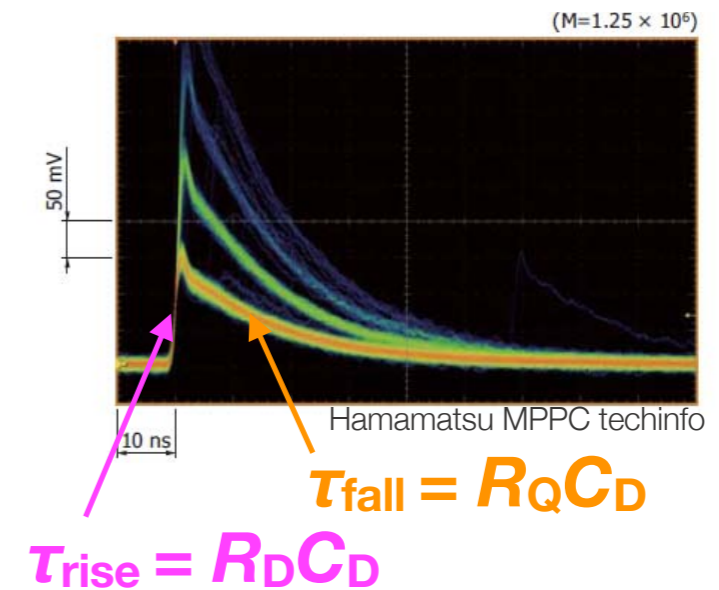
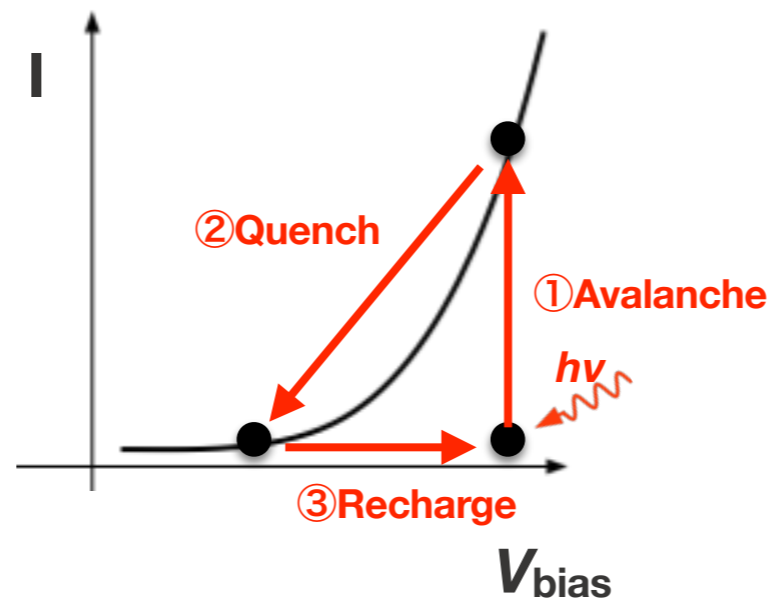
R_D : series resistance of micro-plasma in avalanche

C_D : cell capacitance

V_{bd} : breakdown voltage

V_{bias} : bias voltage

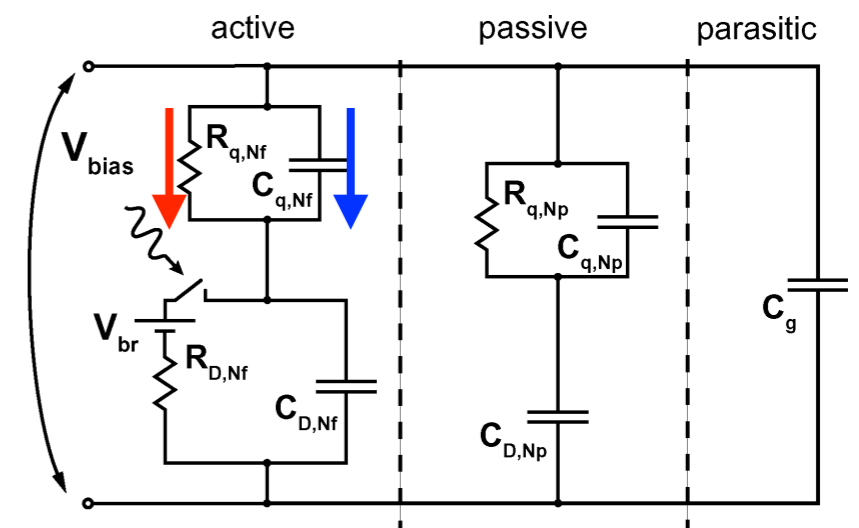
R_Q : quench resistor



Pulse Shape

- More complicated response in reality due to
 - Parasitic capacitance of quench resistor
 - Parasitic capacitance of neighbouring cells
- Two components (fast and slow)
 - **Slow**: slow recharge through quench resistor (R_q)
 - **Fast**: fast discharge through parasitic capacitance of quench resistor (C_q)
 - Fast component is only visible in case of large R_q

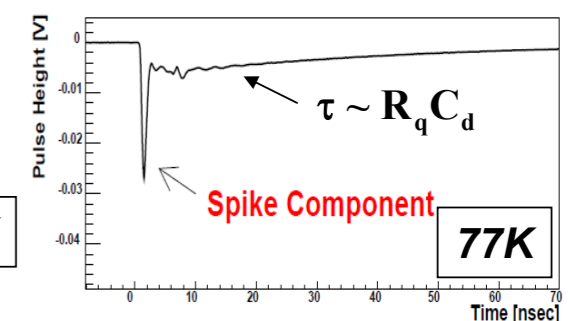
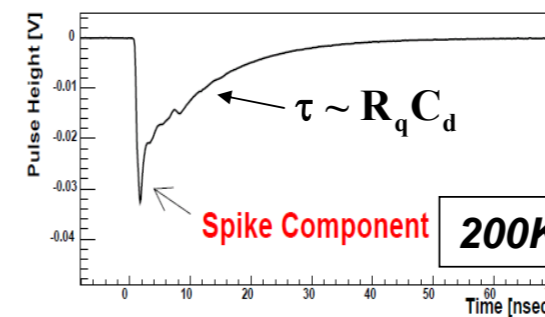
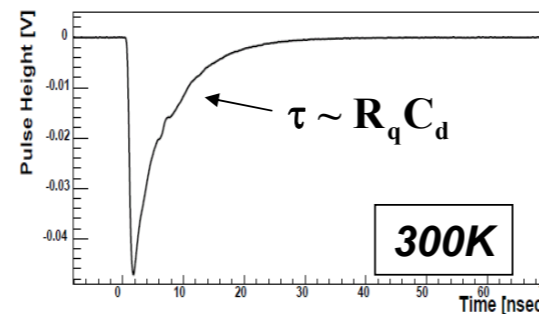
Equivalent circuit for SiPM



S.Seifert et al., IEEE TNS 56(2009)3726

| | 300K | 200K | 77K |
|-------|----------------|----------------|----------------|
| R_q | 0.21M Ω | 0.40M Ω | 1.68M Ω |
| C_q | 22.1fF | 22.0fF | 22.1fF |

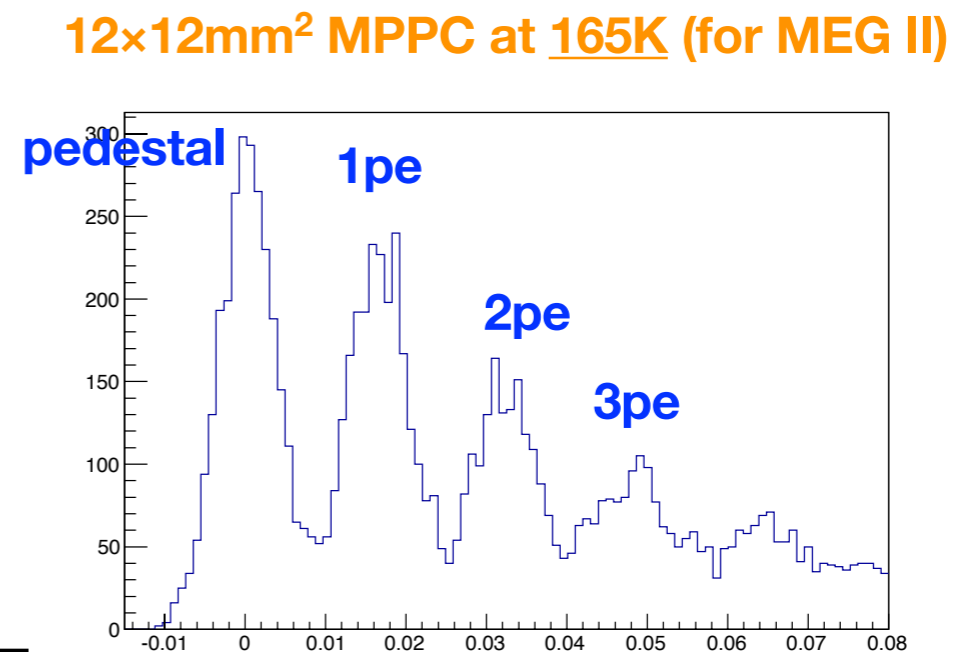
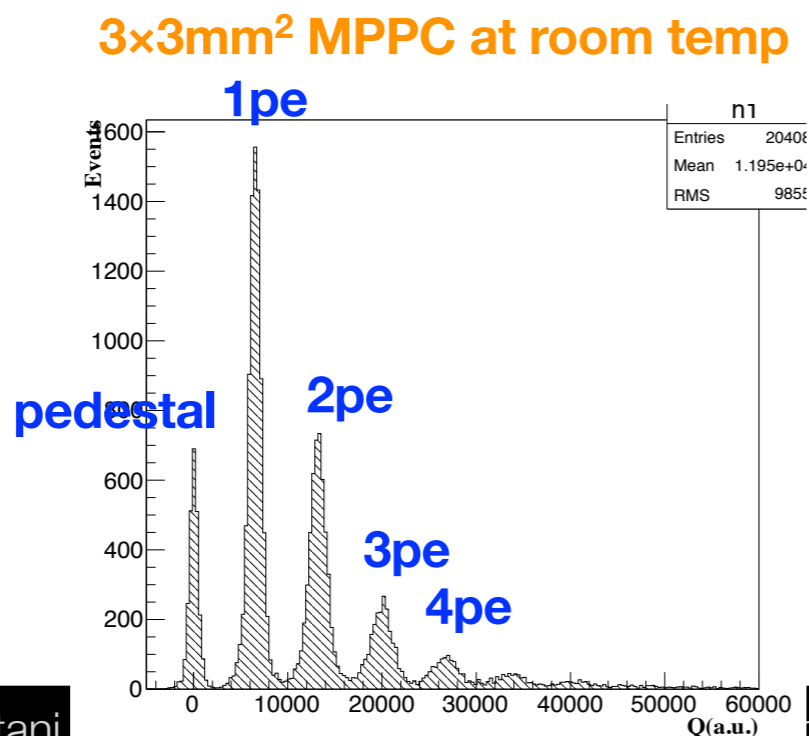
H. Oide et al. PoS(PD07)007



- Signal for light detection: Convoluted with light emission time distribution

Single Photoelectron Resolution

- Excellent single photoelectron resolution because of
 - High internal gain (= good S/N)
 - Good cell-to-cell gain uniformity
 - Can be worsened by electrical noise and pileup due to dark noise and afterpulse
 - Practically single photoelectron peak can not be resolved for $>6\times 6\text{mm}^2$ sensor area due to increasing dark noise
- N.B. Good photoelectron resolution still possible for larger sensor size at low temp.

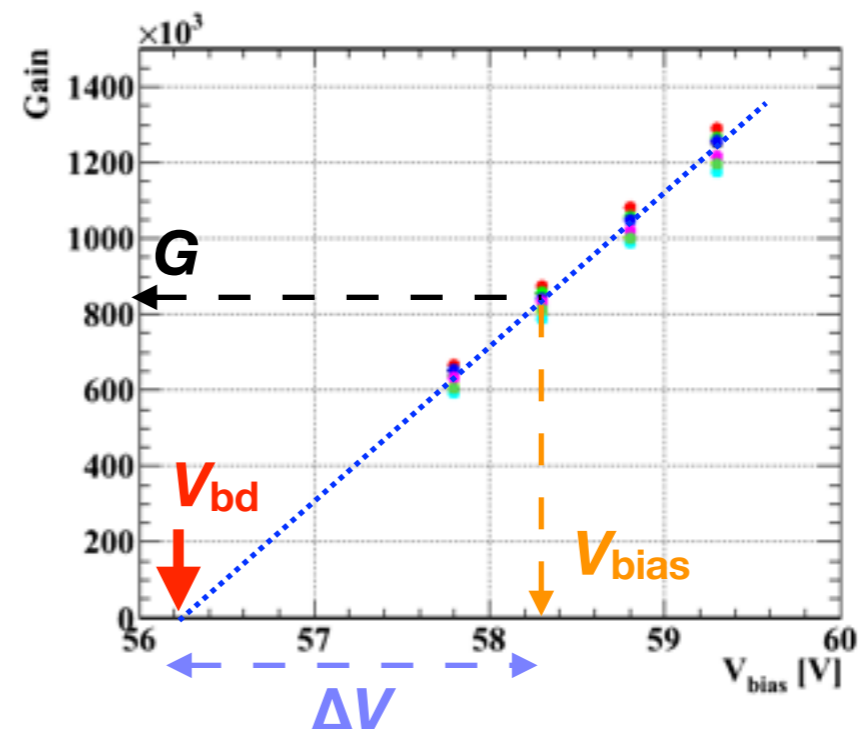
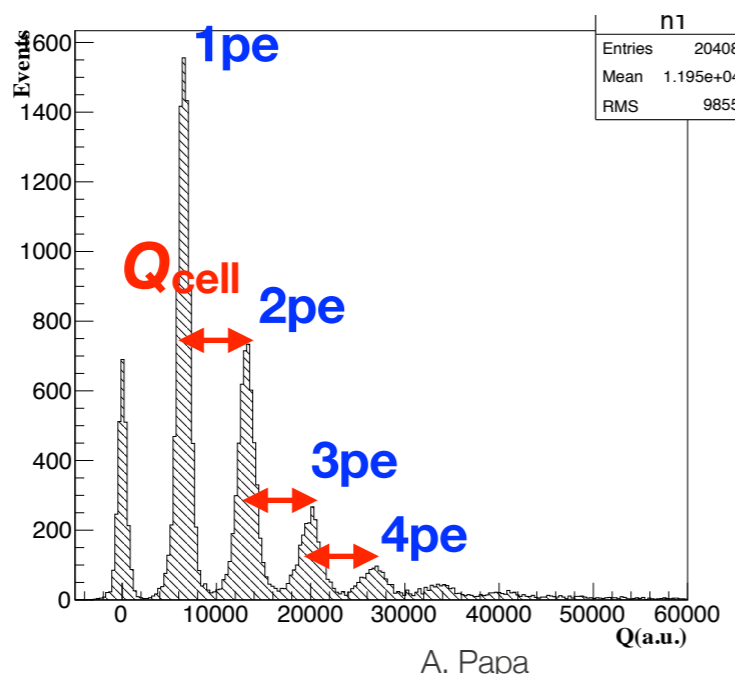


Gain

- High internal gain: 10^5 - 10^6
- Proportional to over-voltage ($\Delta V = V_{\text{bias}} - V_{\text{bd}}$)
- Easily measured from single photoelectron charge
- Gain fluctuation is quite small
 - Cell-to-cell uniformity on capacitance and V_{bd}
 - Small statistical fluctuation in avalanche multiplication (\leftrightarrow Poisson fluctuation in APD)

$$G = \frac{Q_{\text{cell}}}{e} = \frac{C_{\text{cell}} \Delta V}{e}$$

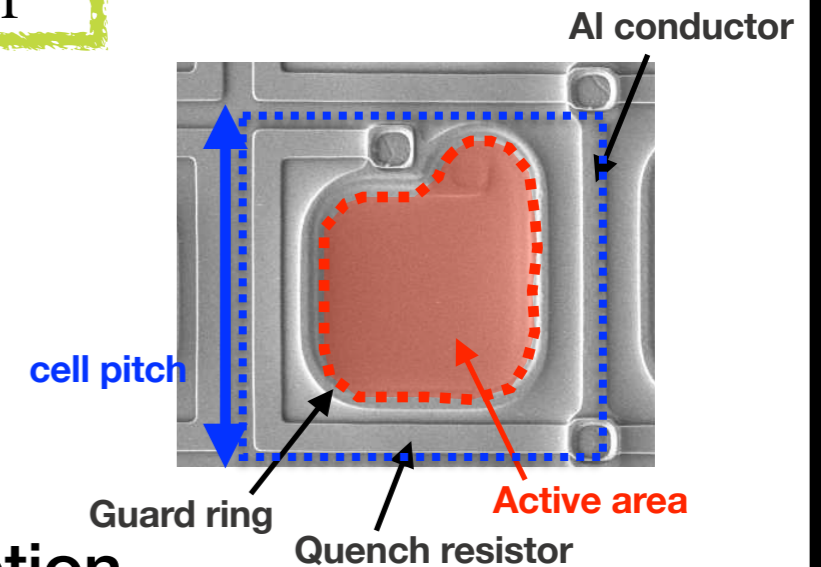
over-voltage $\Delta V = V_{\text{bias}} - V_{\text{bd}}$



Photon Detection Efficiency (PDE)

$$\text{PDE} = \epsilon \times \text{QE} \times P_{\text{trigger}}$$

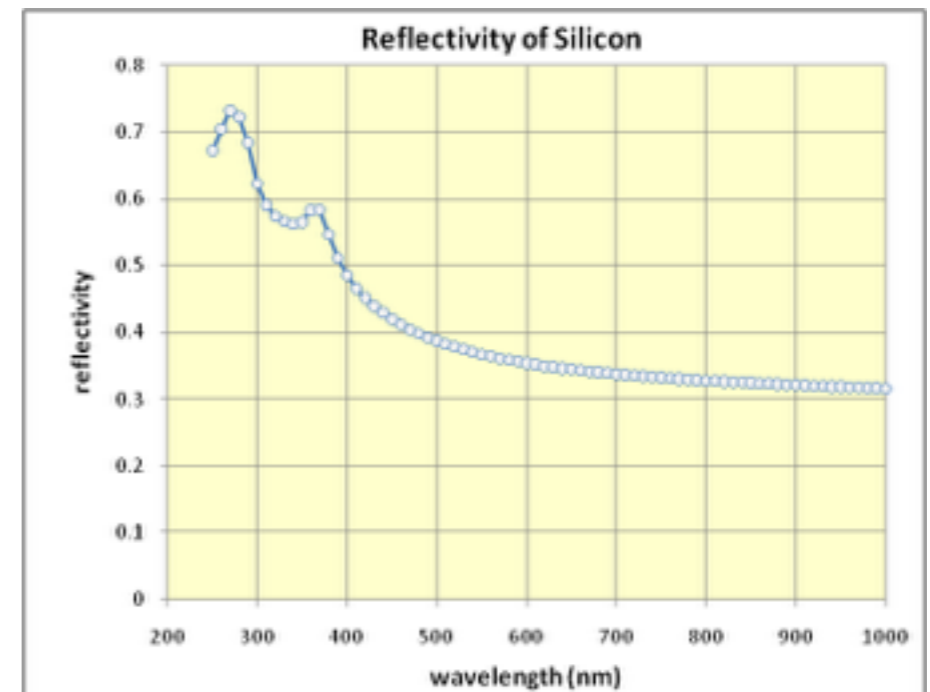
- ϵ (Fill factor)
 - Fraction of active area, typically 50-70%
 - Dead area due to signal line, guard ring, trench,...
- QE (Quantum efficiency)
 - Probability of photo-generation of carrier
 - Dependent on reflectivity on Si surface and absorption length in Si
- P_{trigger}
 - Probability for generated carrier to trigger avalanche
- Dependence on
 - λ
 - ΔV
 - temperature (small)



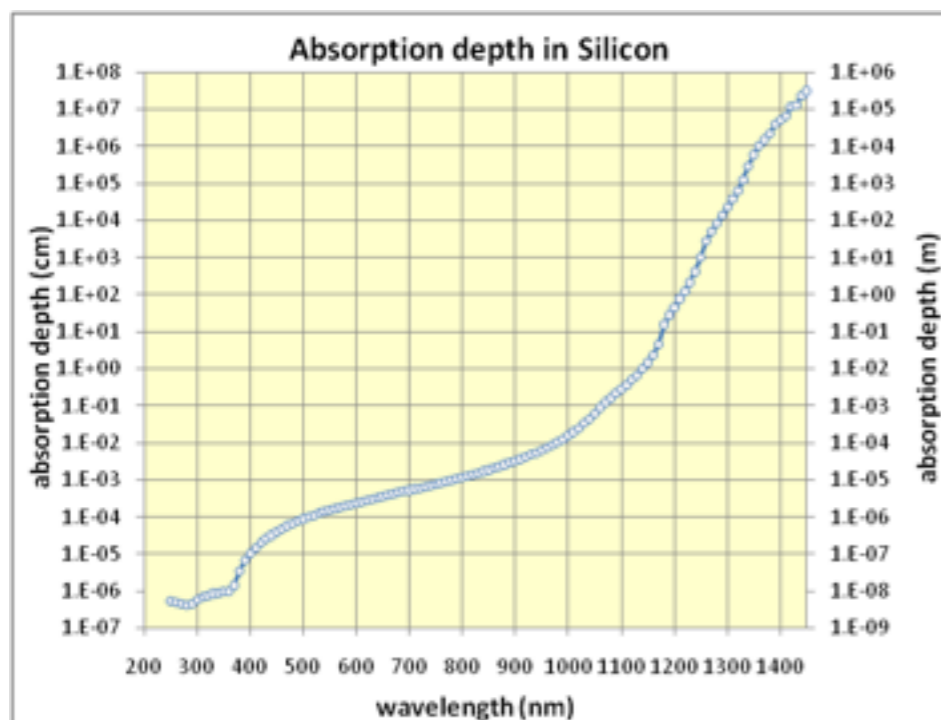
Photon Detection Efficiency (PDE)

Key parameters for QE

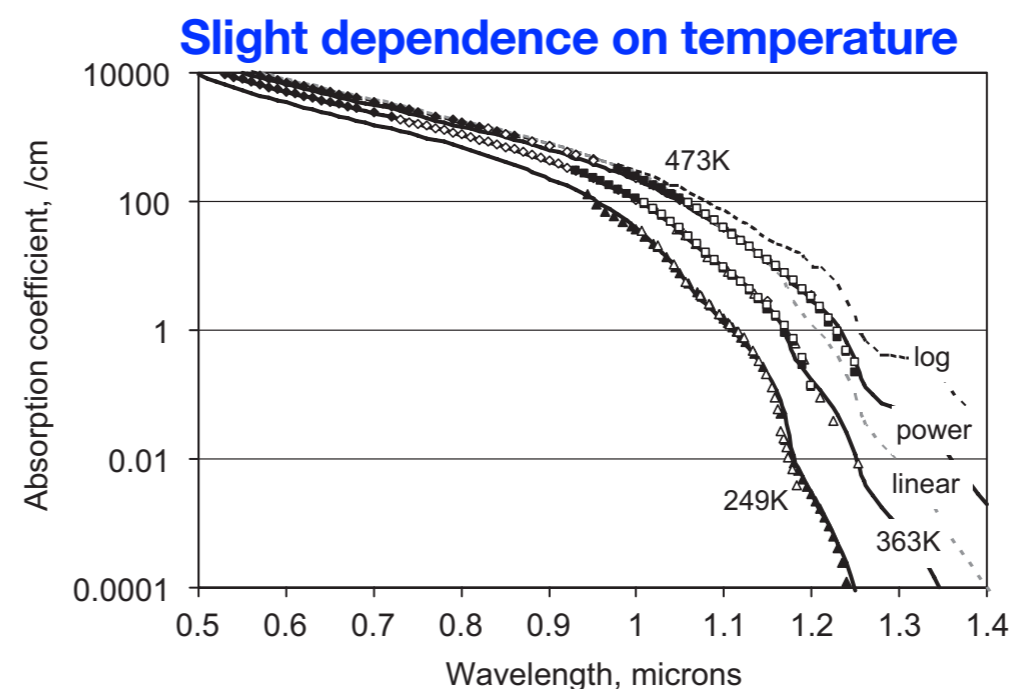
- Reflectivity on Si surface
 - Reflection can be somewhat reduced with AR coating.
- Absorption length in Si depends on λ



PV EDUCATION.ORG homepage



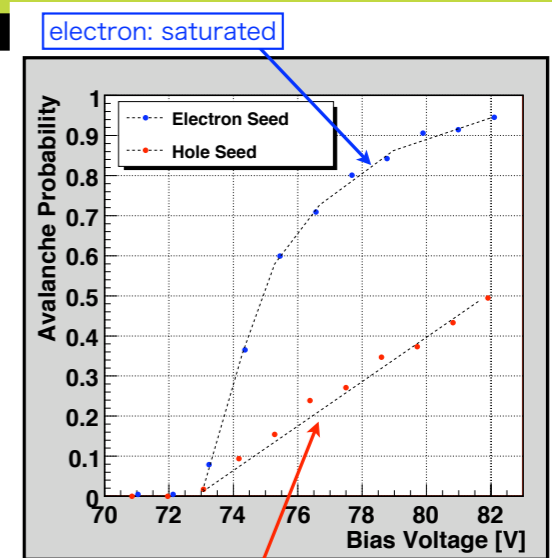
PV EDUCATION.ORG homepage



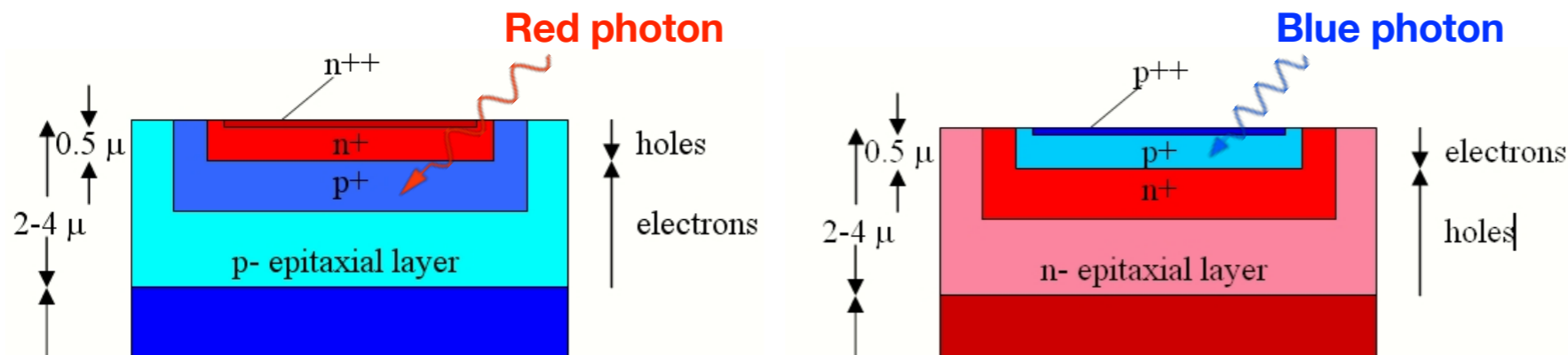
Solar Energy Materials & Solar Cells 92 (2008) 1305– 1310

Photon Detection Efficiency (PDE)

- $P_{\text{trigger}}(\text{electron}) \gg P_{\text{trigger}}(\text{hole})$
 - Higher PDE for carrier generated in p+ layer
- λ -dependence of absorption length in Si
 - Different λ -dependence of PDE depending on depth of p+ layer.

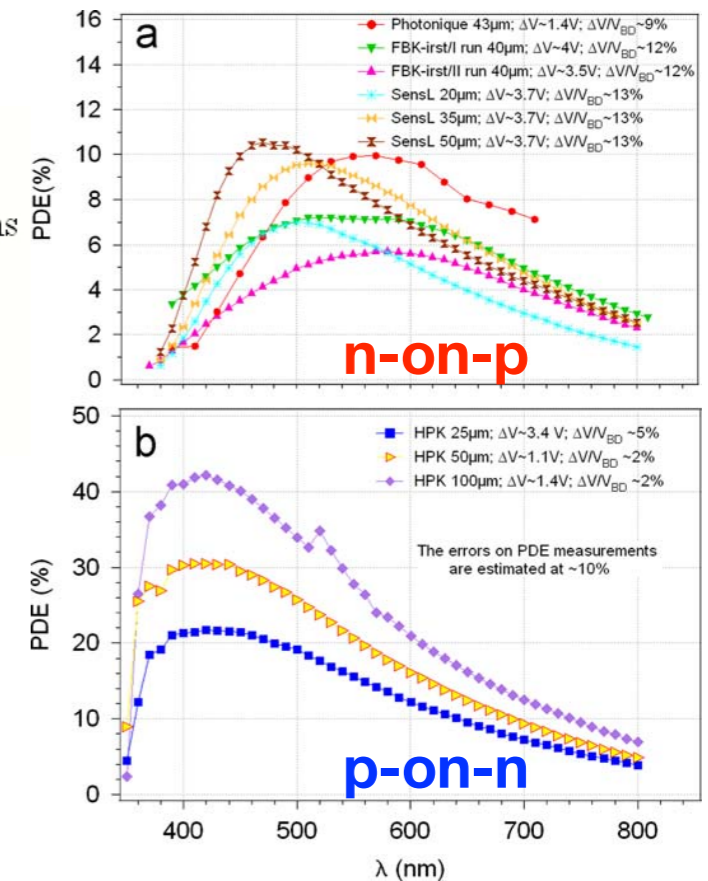


H. Otono, et al., PANIC08



n-on-p structure
→ Green/Red sensitive

p-on-n structure
→ Blue sensitive

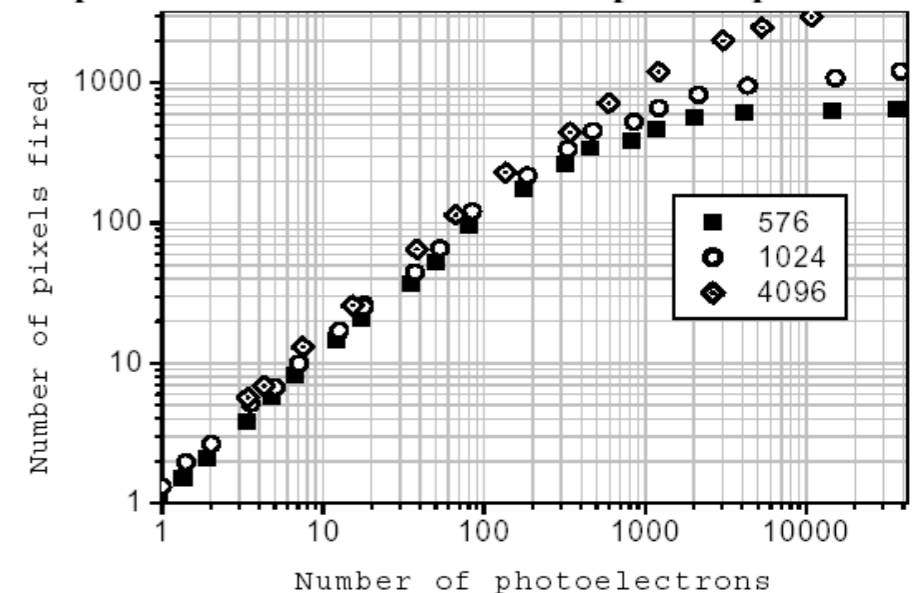


N. Dinu et al., NIMA 610(2009)423

Linearity/Saturation

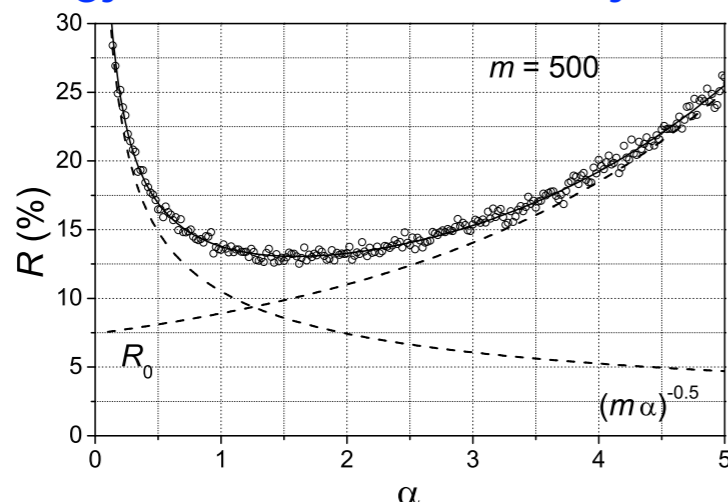
- Good linearity as long as $N_{pe} < N_{cell}$
- Non-linearity (saturation) caused by finite number of cells
- Limiting factors
 - Incoming photon intensity
 - Cell size
 - Recovery time
- Need careful correction for many photons
- How to mitigate saturation → smaller cell

Response functions for the SiPMs with different total pixel numbers measured for 40 ps laser pulses



B. Dolgoshein, TRD2005

Energy resolution worsened by saturation (Simulation)



$m: N_{cell}$
 $n: N_{photon} \times PDE$
 $\alpha = n/m$

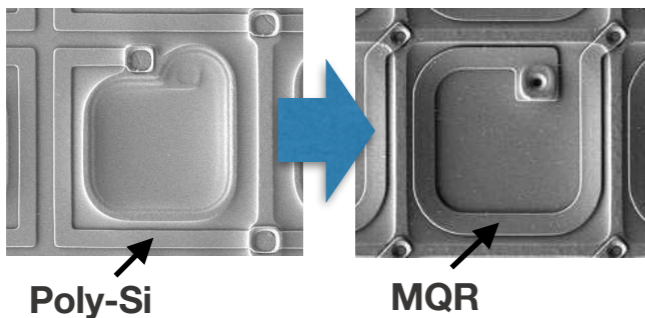
A. Stoykov, et al., JINST 2 P06005

$$N_{fired} = N_{cell} \left(1 - e^{-\frac{N_{photon} PDE}{N_{cell}}} \right)$$

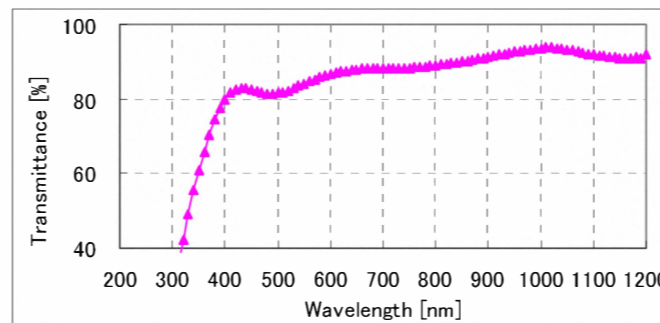
Small Cell SiPM

- 10 μm cell pitch for Hamamatsu MPPC

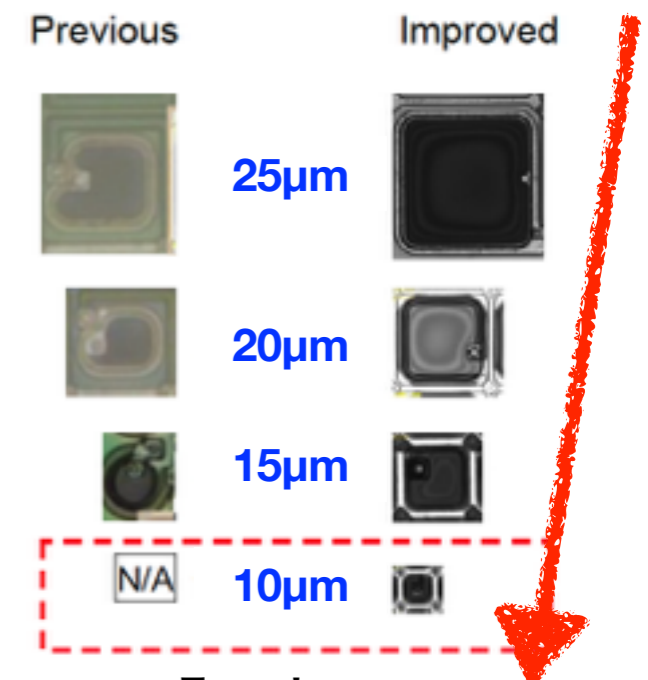
- Fill factor improved by metal quench resistor (MQR)
- Thin MQR (\Leftarrow transparent to light) over active area!



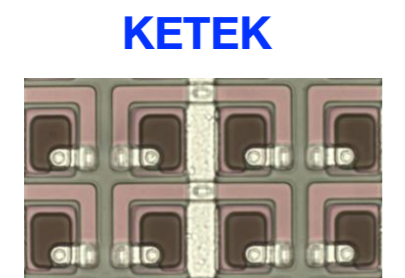
K. Sato et al., IEEE TNS 2013



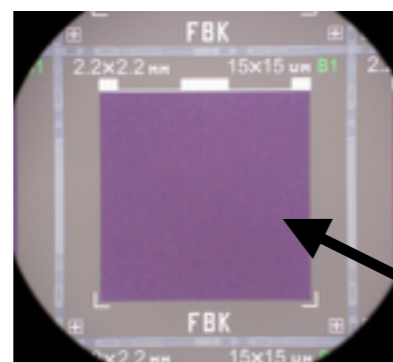
T.Nagano et al., IEEE TNS 2011



- 15 μm cell pitch for KETEK and AdvanSiD

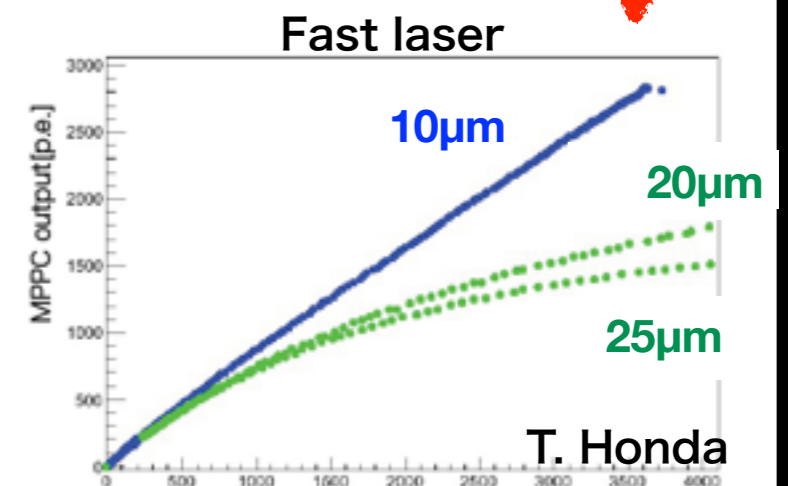
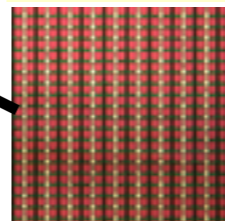


KETEK



FBK-AdvanSiD

Active area: 2.2x2.2 mm²
 cell size: 15x15 μm^2
 # cells: ~ 21300
Fill factor = 48%



T. Honda

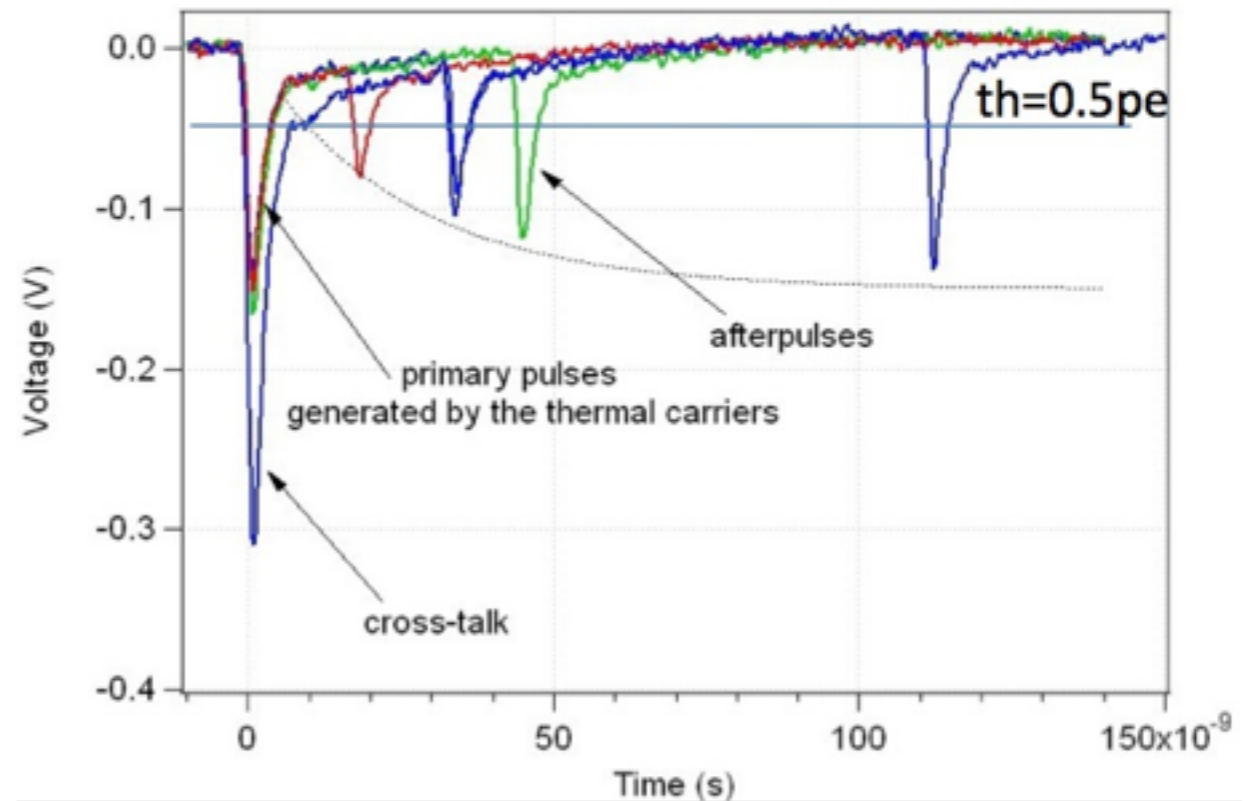
- Micro-cell: Micro-pixel APD (MAPD) from Zecotek

- Up to 40,000 cell/mm²

Noise in SiPM

Intrinsic noise source of SiPM

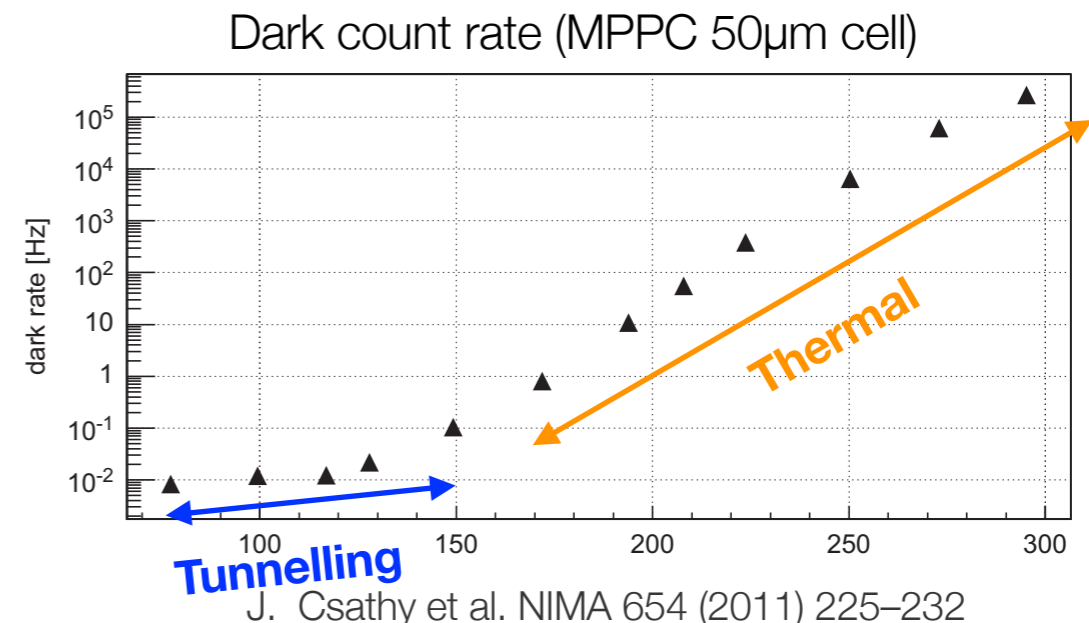
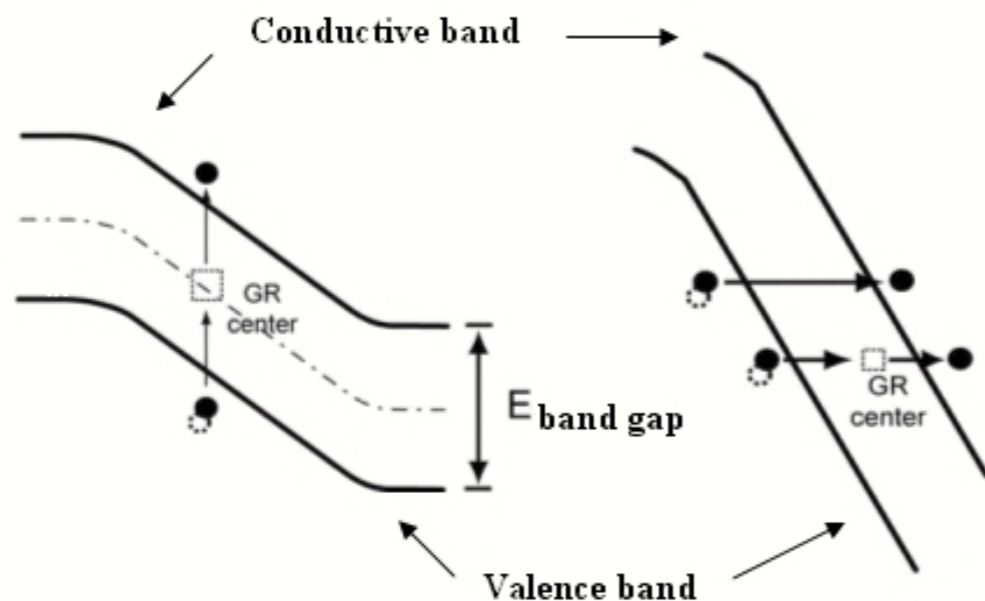
- **Dark noise**
 - Thermally generated carrier
 - Random
- **Correlated noise**
 - Optical cross-talk
 - After-pulsing
- **Correlated noise increases gain fluctuation and thus increases excess noise factor (ENF).**
 - Energy resolution is deteriorated with increased ENF.



$$ENF = 1 + \frac{\sigma_G^2}{G^2}$$

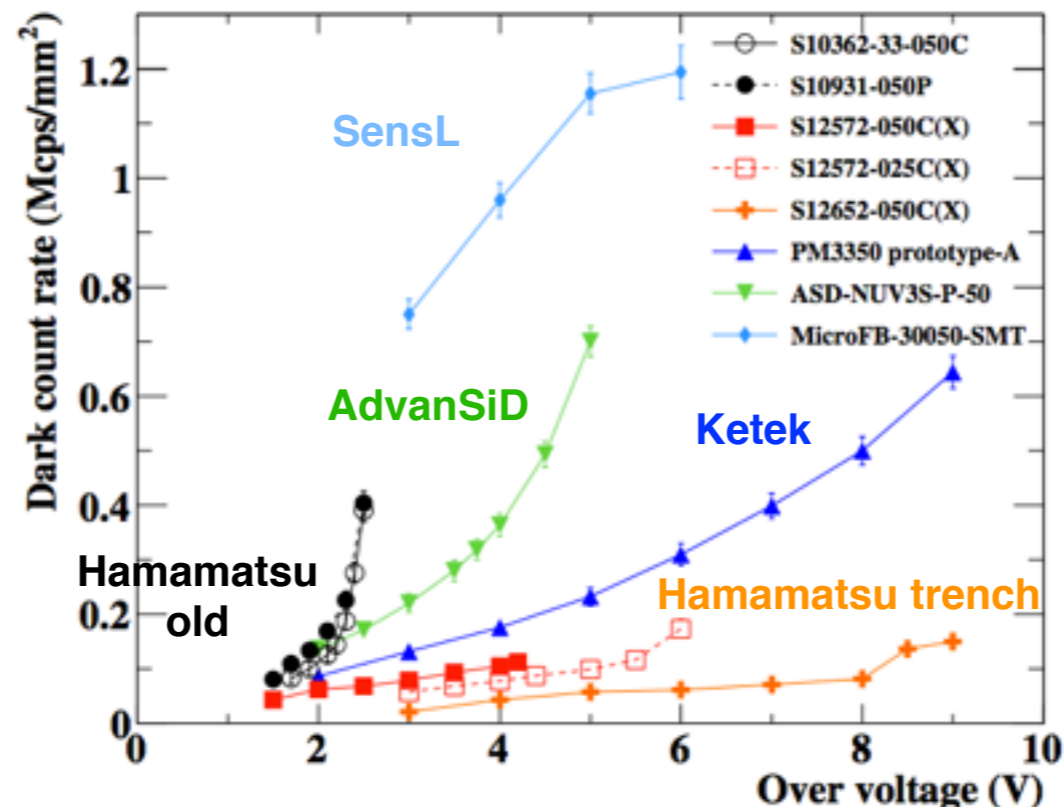
Dark Noise (Dark Count)

- Signal from avalanche triggered by randomly generated carrier
- Two sources
 - Thermal generated
 - Dominates at room temperature
 - Drastically reduced at low temperature (A factor of two every 8 deg. temperature drop)
 - “Field-assisted” generation (Tunnelling)
 - Dominates at $T < 200\text{K}$



Dark Noise (Dark Count)

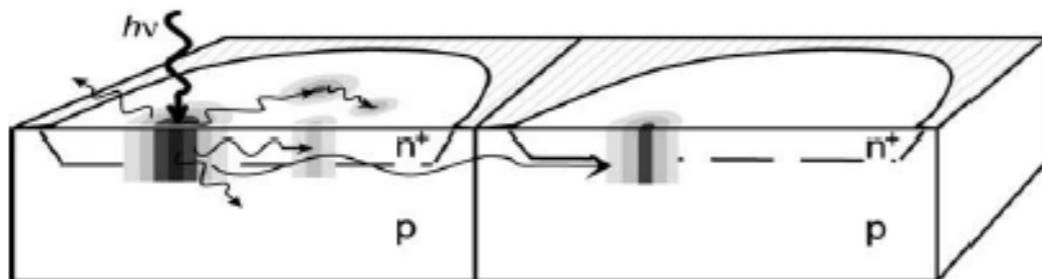
- Dark count rate improved as $<50\text{kHz}/\text{mm}^2$ for recent devices
 - Improved wafer quality
 - Improved processing of epitaxial layer
 - Impurity getter
- Easy solution: Setting higher threshold ($>1\text{pe}$, 2pe , ...)



P. W. Cataneo, WO, et al. IEEE-TNS 61(2014)2657

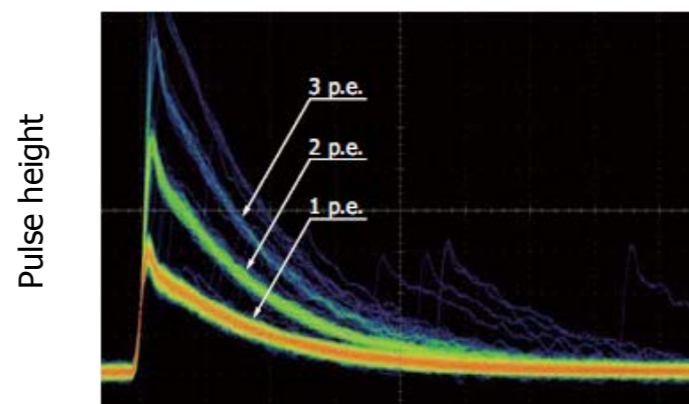
Optical Cross-talk

- NIR luminescence during avalanche:
 - ~3 photons generated for 10^5 carriers (A. Lacaita et al., IEEE TED 1993)
- Photon can generate carrier in neighbouring cell and then induce another avalanche.
- Superimposed on the primary pulse at the same timing.

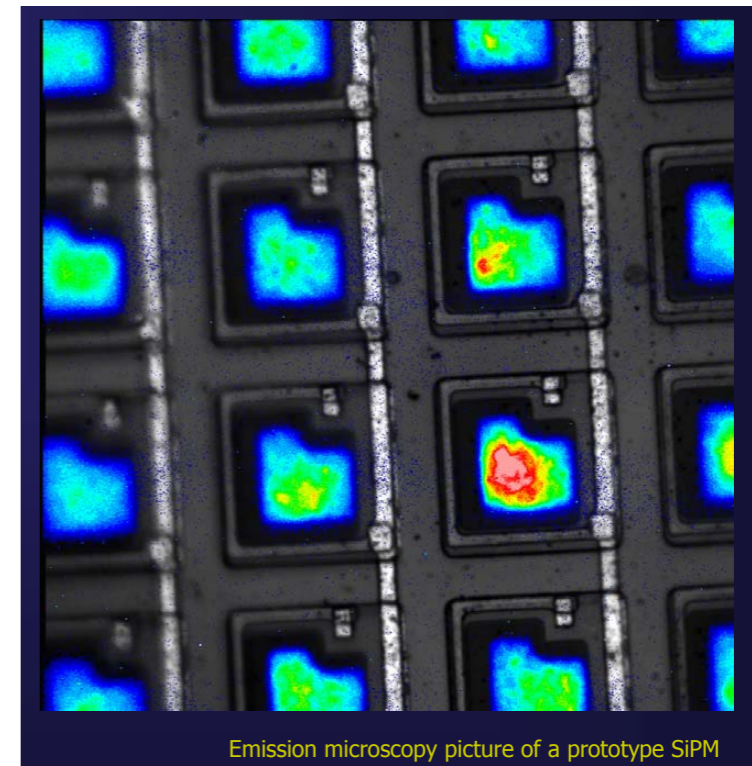


A. Lacaita et al., IEEE TED 2013

Optical crosstalk superimposed on primary pulse



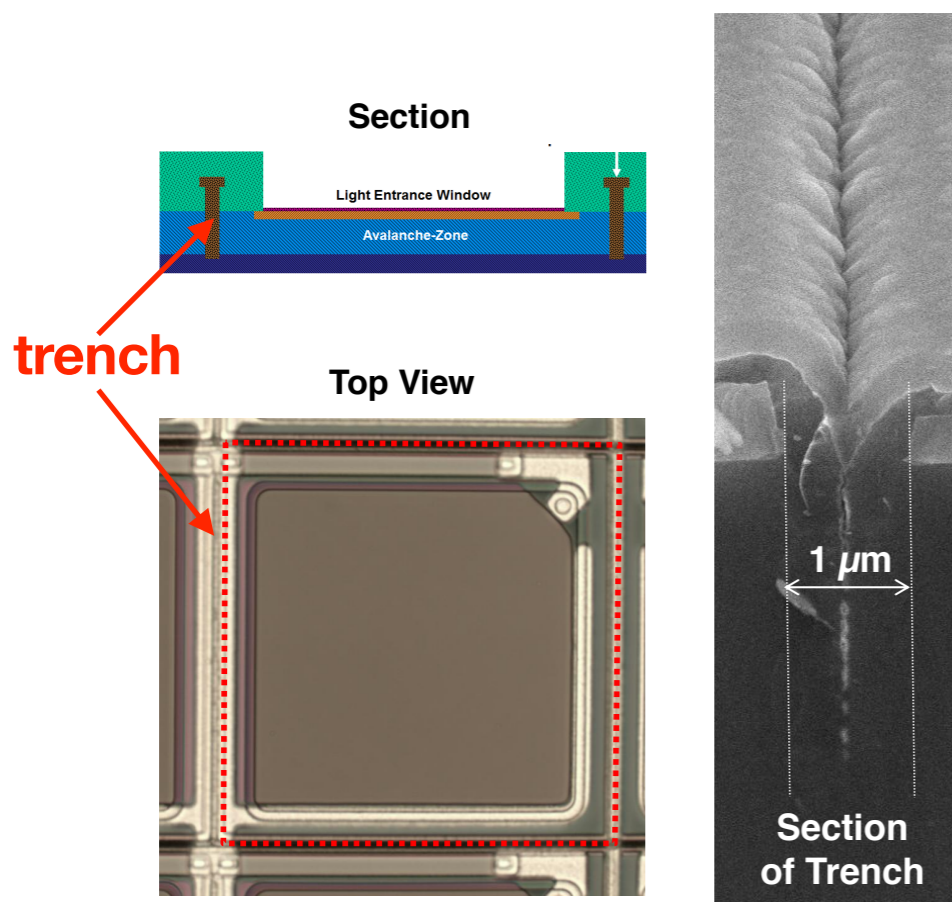
Time Hamamatsu MPPC techinfo



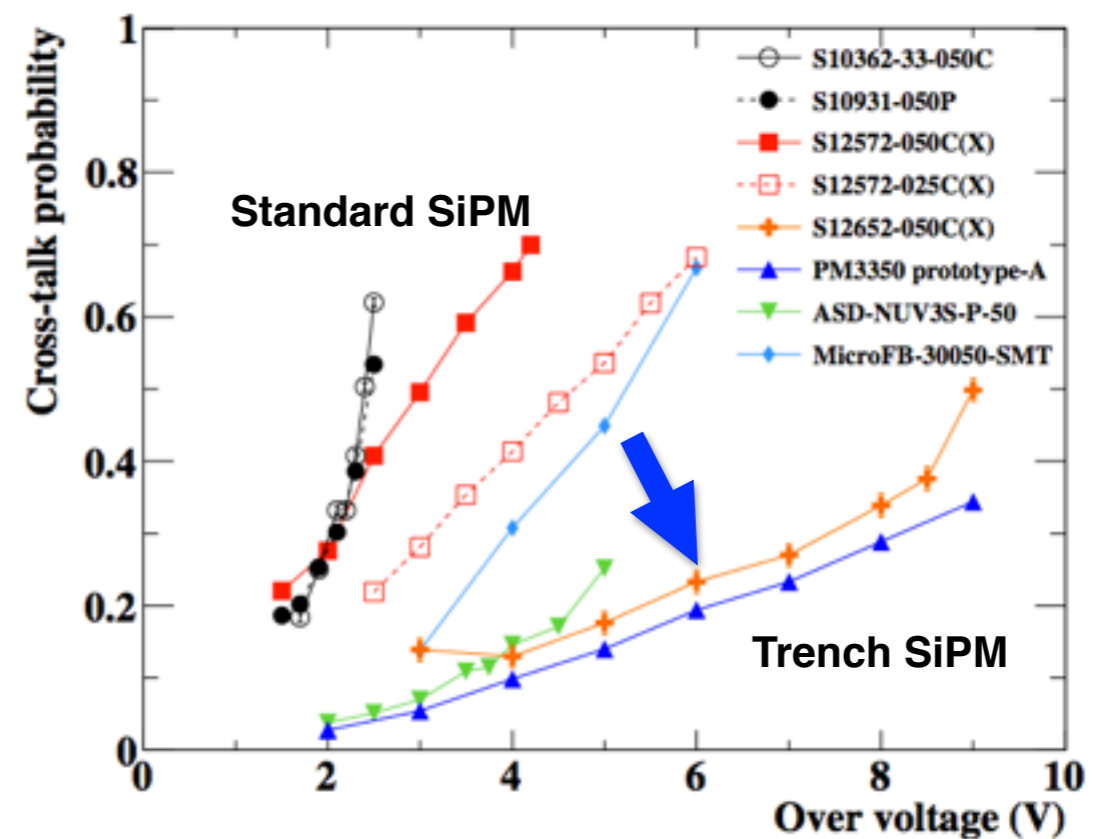
N. Otte, SNIC2006

Optical Cross-talk

- Optical cross-talk can be reduced by
 - Lower bias voltage (at the cost of lower gain/PDE)
 - Smaller cell
 - Cell isolation by trench filled with opaque material



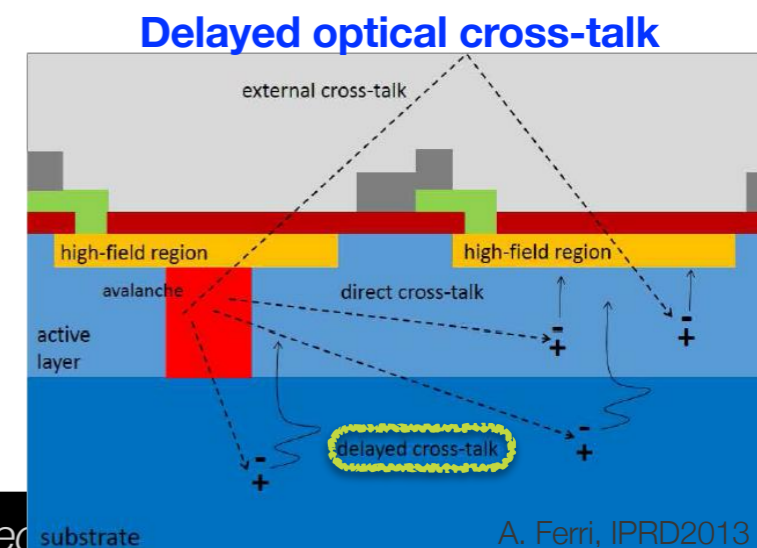
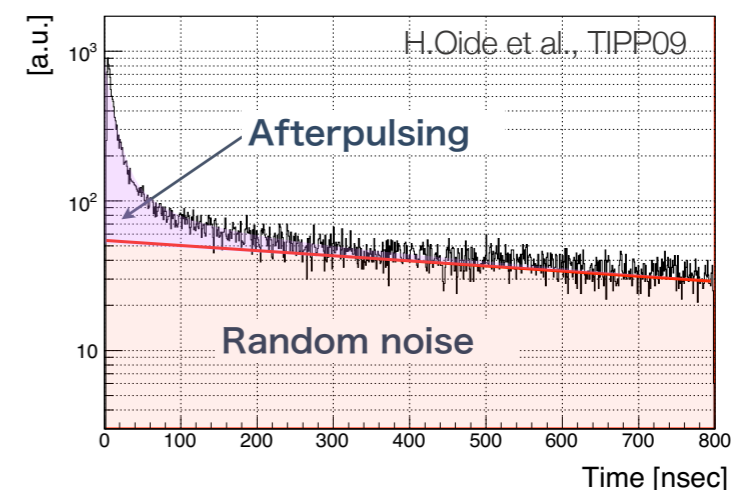
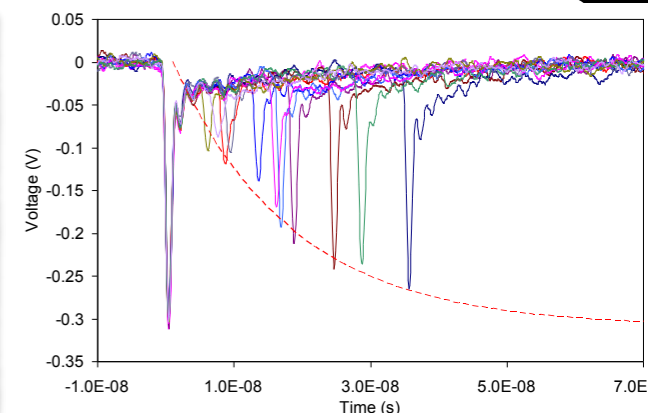
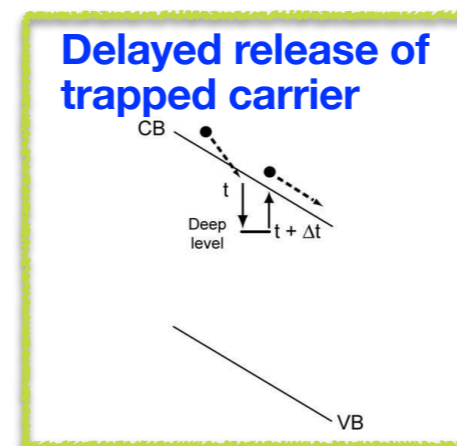
F. Wiest et al., PhotoDet2012



P. W. Cataneo, WO, et al. IEEE-TNS 61(2014)2657

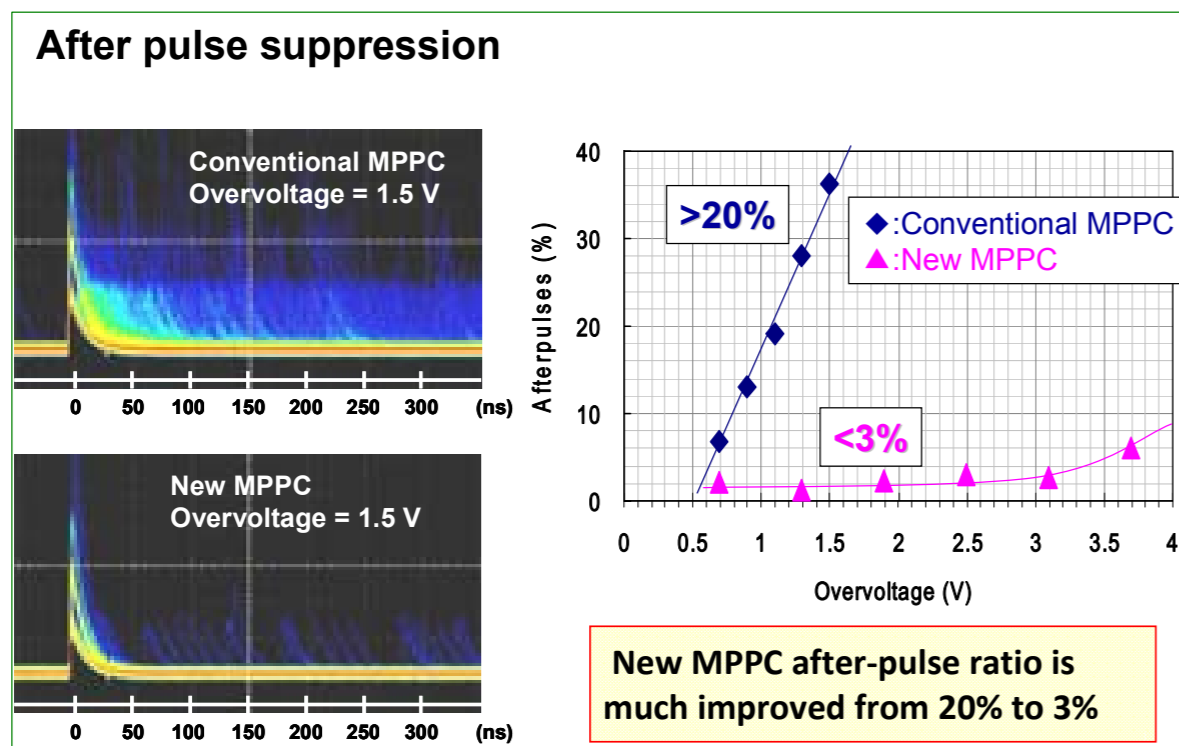
After-pulsing

- Delayed correlated noise
- Two sources
 - Delayed release of trapped carrier
 - Some carriers from primary avalanche are trapped in a deep trapping level in energy band gap \rightarrow delayed release \rightarrow trigger another avalanche
 - ΔV^2 dependence ($N_{\text{carrier}} \propto \Delta V$, $P_{\text{trigger}} \propto \Delta V$)
 - Solutions
 - Better quality of wafer and epi. layer
 - Reduced gain
 - Delayed optical cross-talk
 - Solutions: Buried junction to block delayed carrier diffusion from substrate



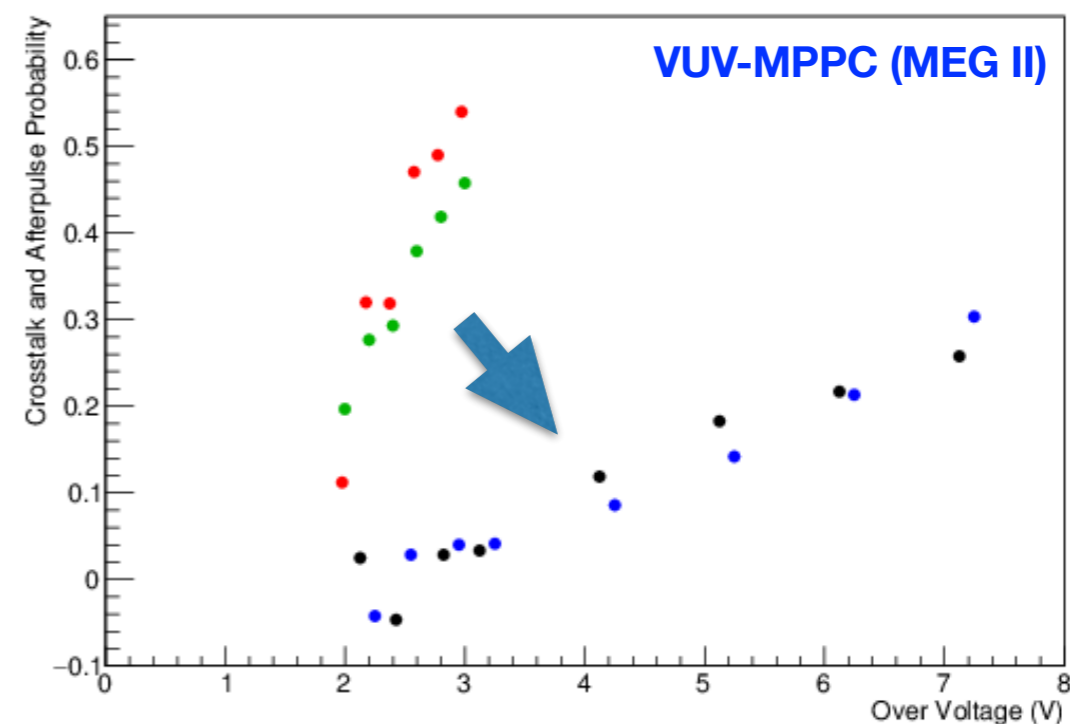
After-pulsing

- After-pulsing drastically reduced for recent Hamamatsu MPPC



K. Sato, et al., VCI2013

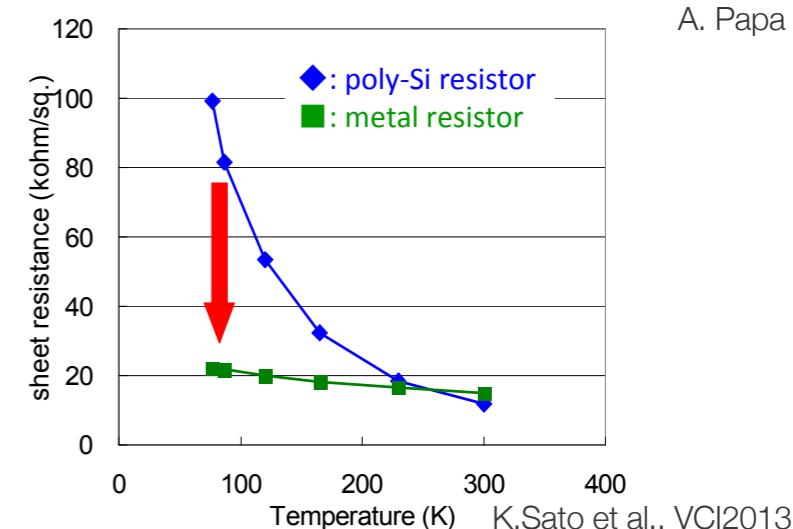
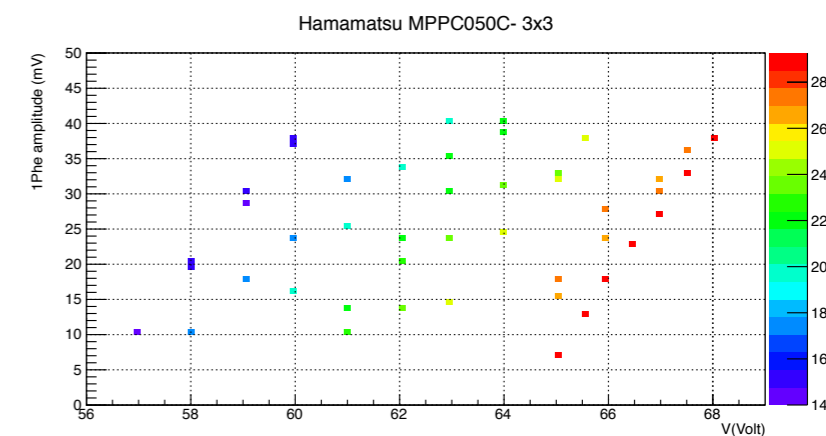
Probability of Crosstalk+Afterpulse



- Both cross-talk and after-pulsing drastically reduced at the same device!
- **Bonus:** Operational at higher bias voltage → higher gain/PDE

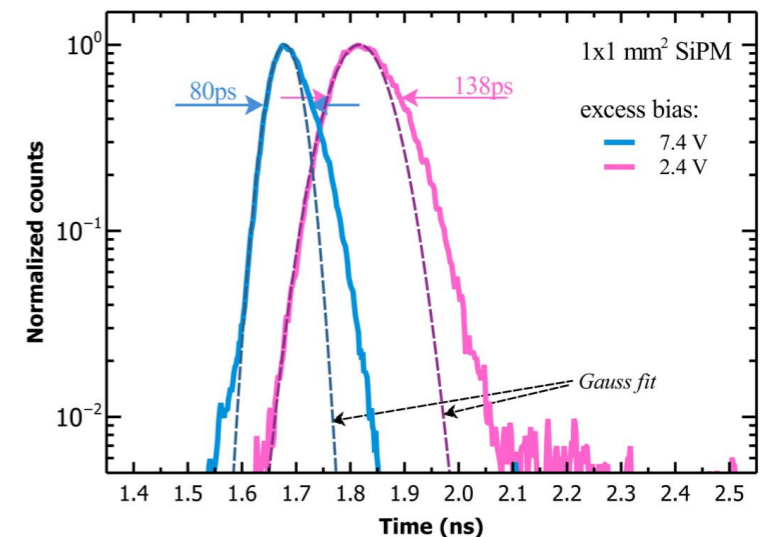
Temperature Dependence

- In general, SiPM has to be operated at controlled temperature. ☹️
- Temperature dependence of SiPM
 - Breakdown voltage
 - $\Delta V_{bd} / \Delta T = 55\text{mV/deg}$ (MPPC), 25mV/deg (AdvanSiD)
 - Gain can be drastically changed when temperature varies, if V_{bias} is not adjusted accordingly.
 - Dark count rate
 - $\times 2$ reduction every 8deg temp. reduction
 - Quench resistor
 - Signal shape can be changed.
 - Improved by using metal quench resistor instead of poly-Si (Hamamatsu MPPC)

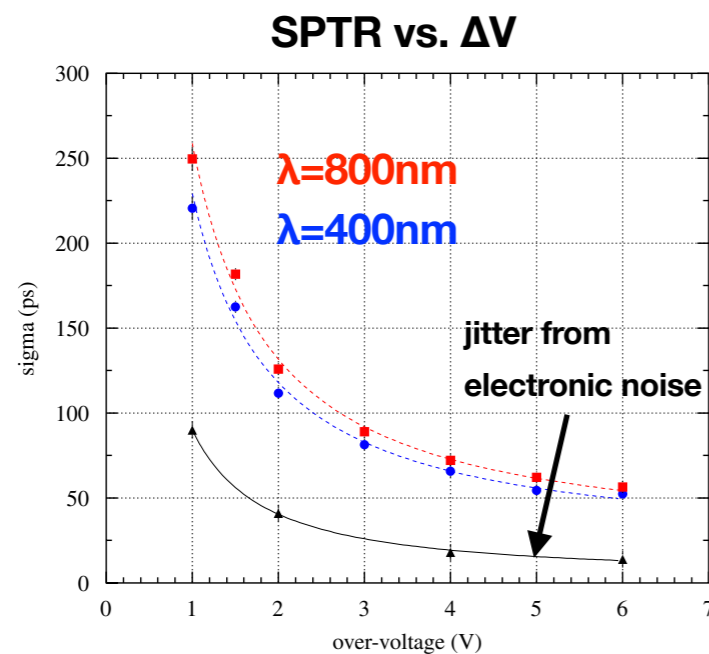


Timing Resolution

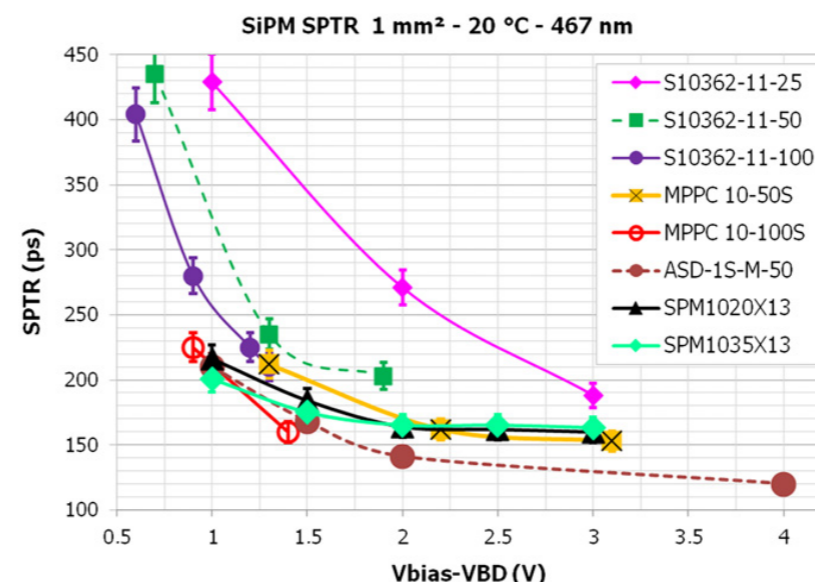
- SiPM signal charge generated in very thin layer (~a few μm)
- SiPM has an excellent Single Photon Time Resolution (SPTR).
 - Major component: Gaussian jitter $\sim O(100\text{ps})$ (FWHM)
 - Minor slow tail ($\sim O(\text{ns})$) from carrier drift from neutral region
- Strong dependence on ΔV , weak dependence on λ



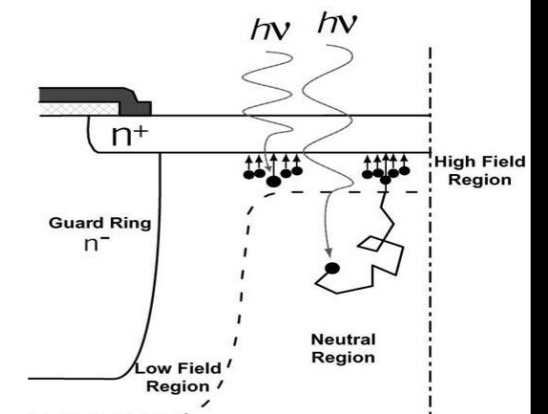
F. Acerbi et al., IEEE-TNS 61(2014)2678



G. Collazuol et al., NIMA 581(2007)461



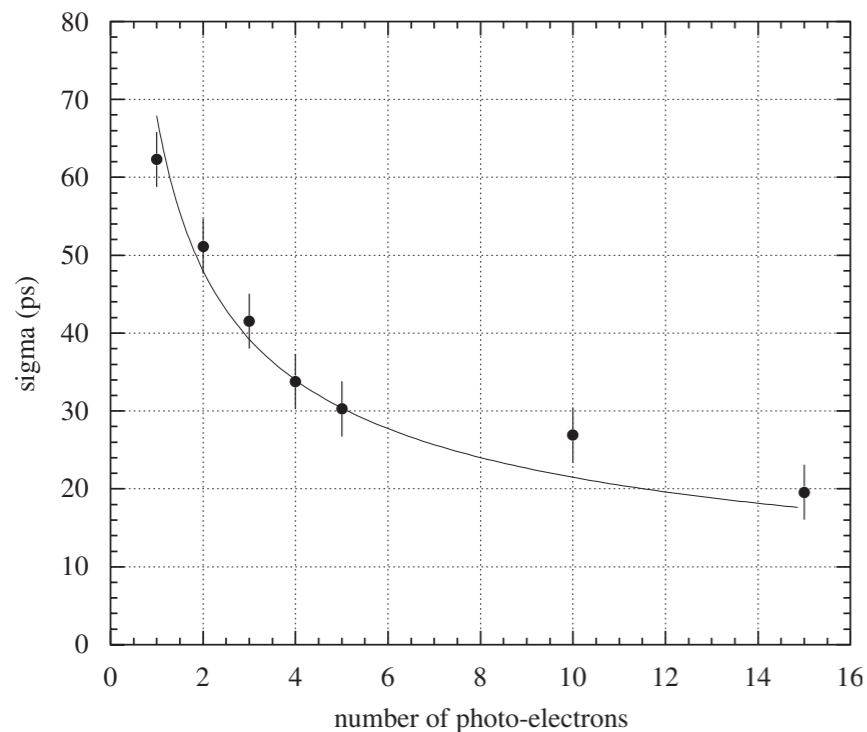
V. Puill et al., NIMA 695(2012)354



S. Cova et al., NIST Workshop on Single Photon Detectors 2003

Timing Resolution

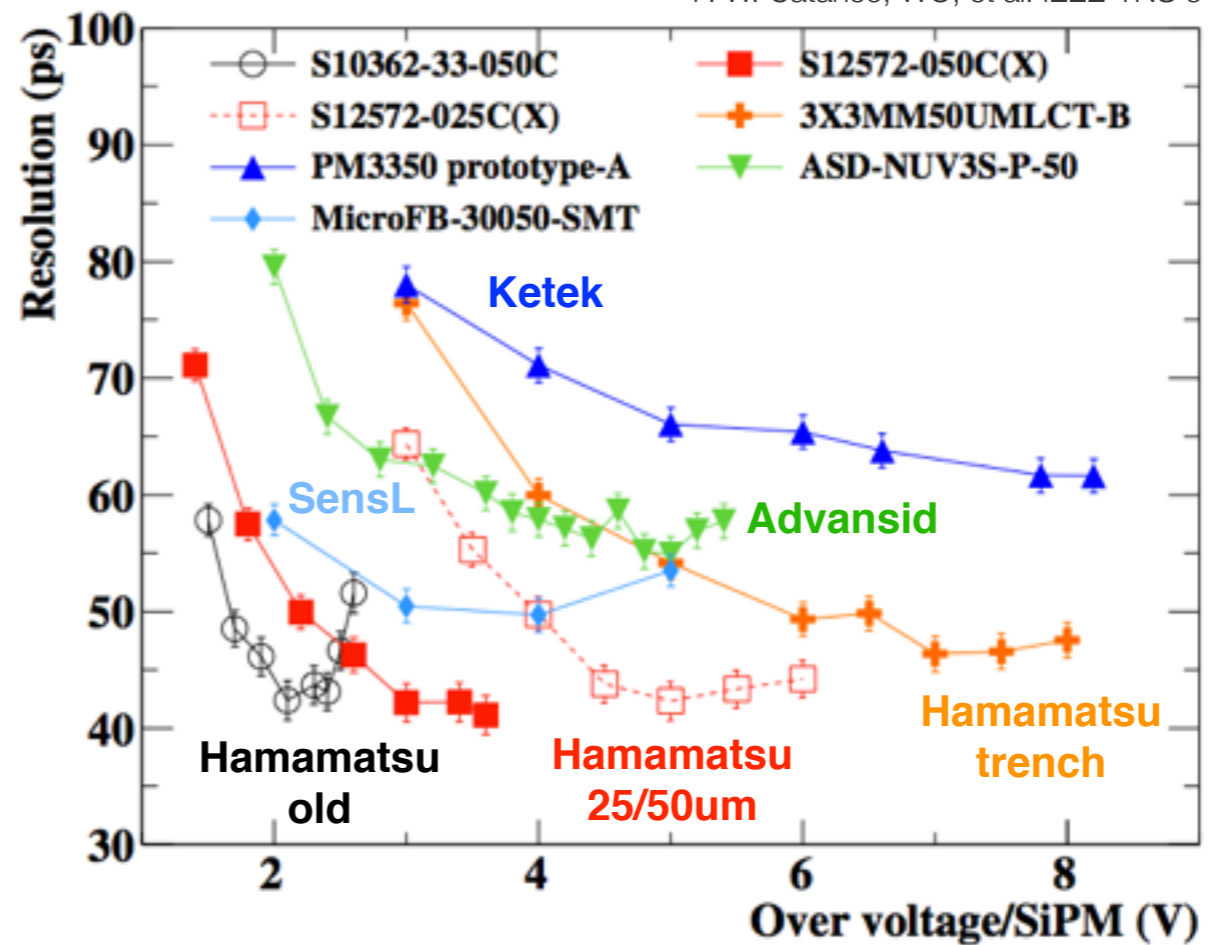
- Timing resolution for many photons



G. Collazuol et al., NIMA 581(2007)461

Fast plastic scintillator (BC422 60x30x5mm³)
readout by 6 SiPMs

P. W. Cataneo, WO, et al. IEEE-TNS 61(2014)2657



- Better resolution at higher ΔV (gain, PDE, SPTR)
- Saturated due to dark noise or after-pulsing

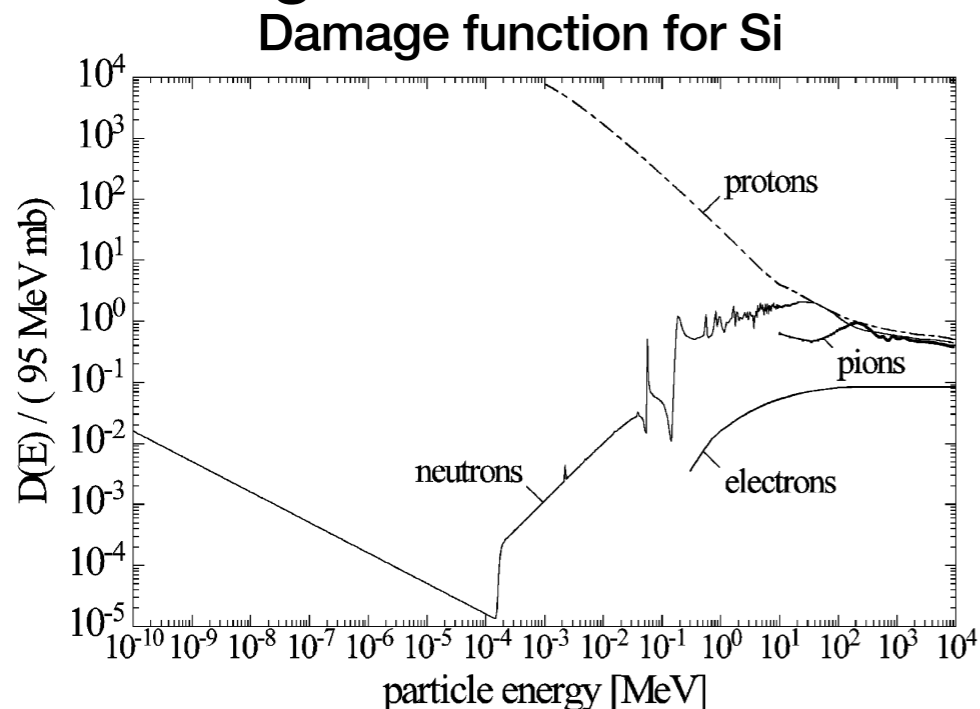
Radiation Hardness

- Radiation damage of SiPM

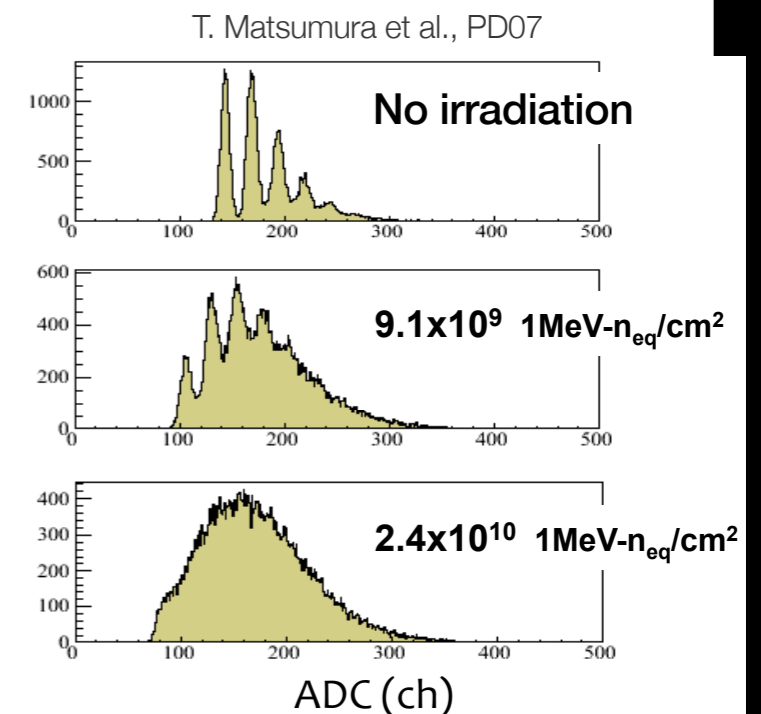
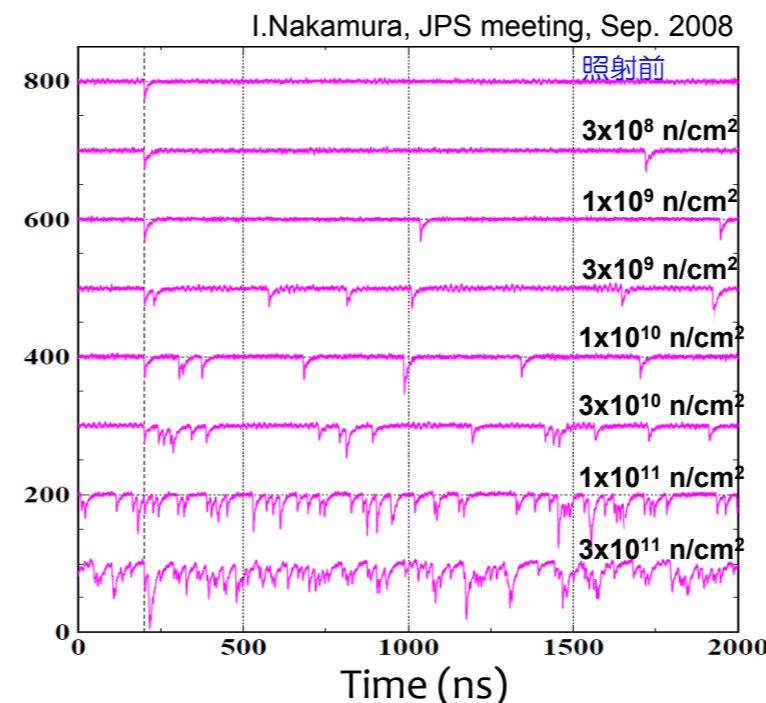
- Neutron, Proton → Bulk damage by Non-Ionizing Energy Loss (NIEL)
- γ -ray, X-ray → Damage of Si-SiO₂ interface by ionizing energy loss → Charge trap at interface

- Effect of radiation damage

- Increase of dark noise
- Change in breakdown voltage, gain and PDE



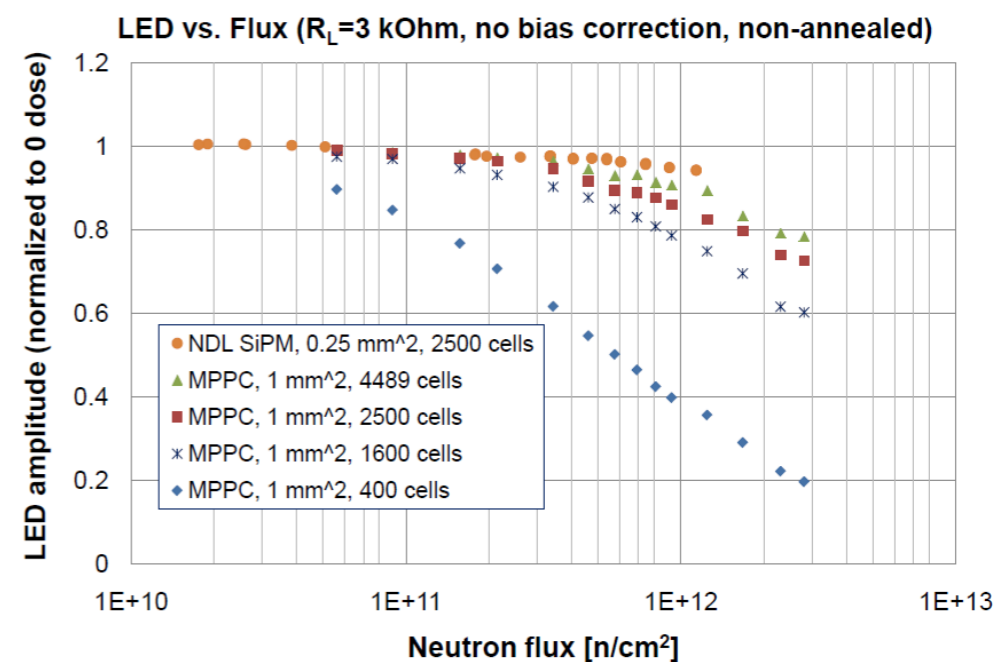
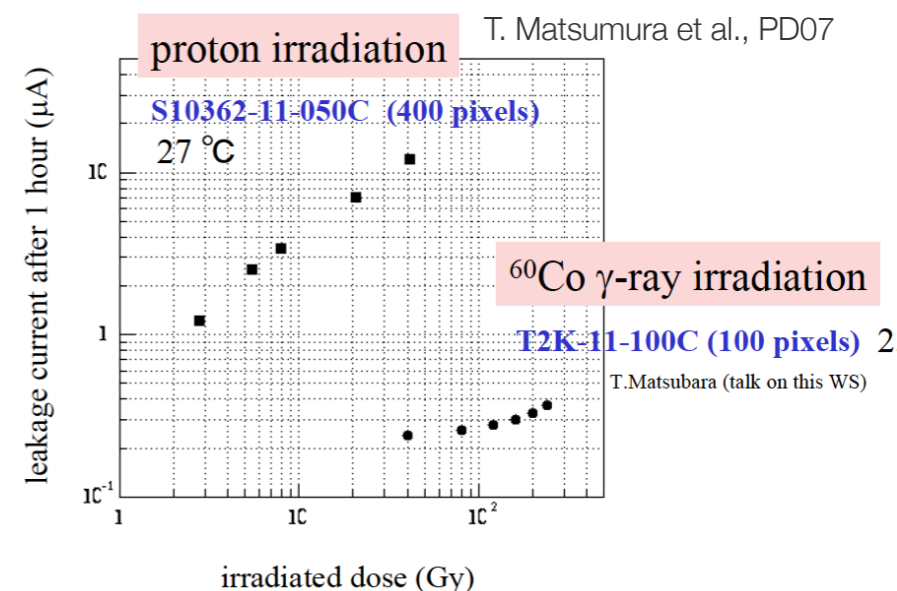
G. Lindstrom, et al., NIMA 426(1999)1



Radiation Hardness

Effect of radiation damage

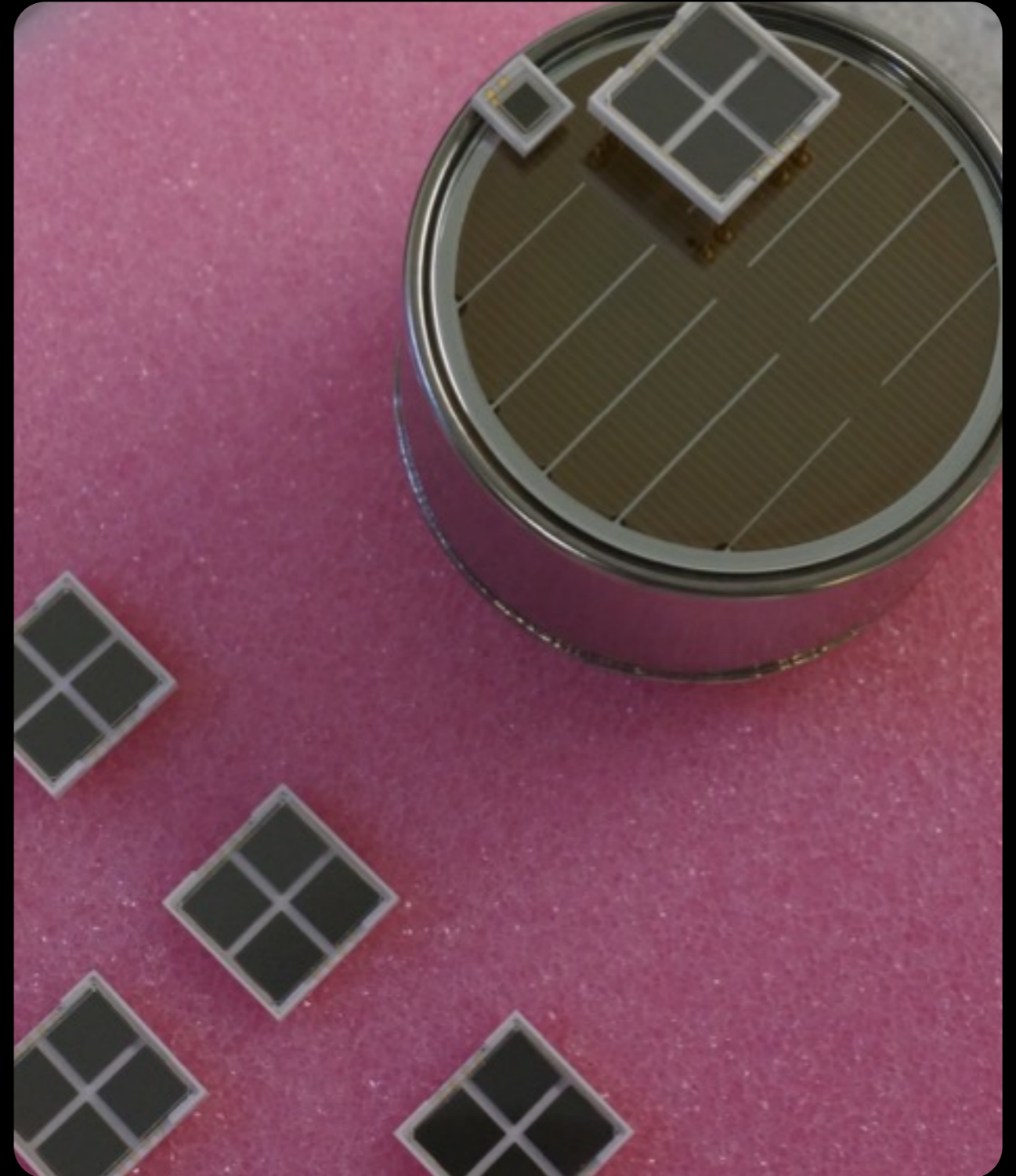
- Neutron/proton
 - $>10^8$ 1MeV- n_{eq}/cm^2 : increase of dark noise
 - $>10^{10}$ 1MeV- n_{eq}/cm^2 : loss of single photoelectron resolution
- γ -ray
 - ~ 200 Gy: local breakdown
- Damage effect for proton: 1-2 orders larger than γ -ray
- Possible solution for radiation hardness
 - Reduce volume to be damaged
 - Thinning down epitaxial layer \leftarrow smaller cell
 - Thinning down substrate
 - Better insulator material for surface damage?
 - Other material? Not “Si”PM any more...



Y. Musienko, CERN SiPM workshop 2011

Contents

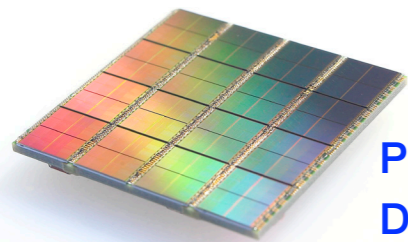
- Introduction
- Properties and Performance
- **New Developments**
- Application Examples
- Summary



Digital SiPM

- **Digital SiPM (dSiPM) from Philips**

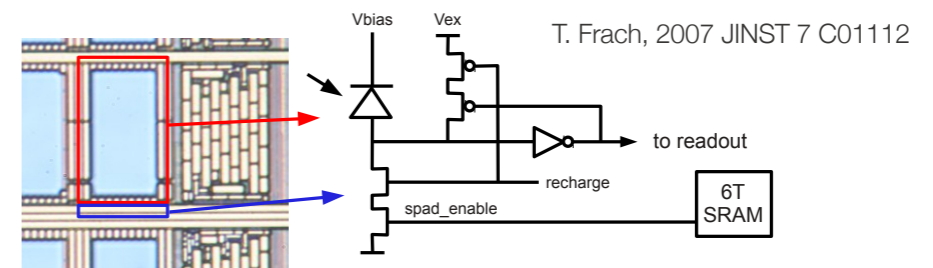
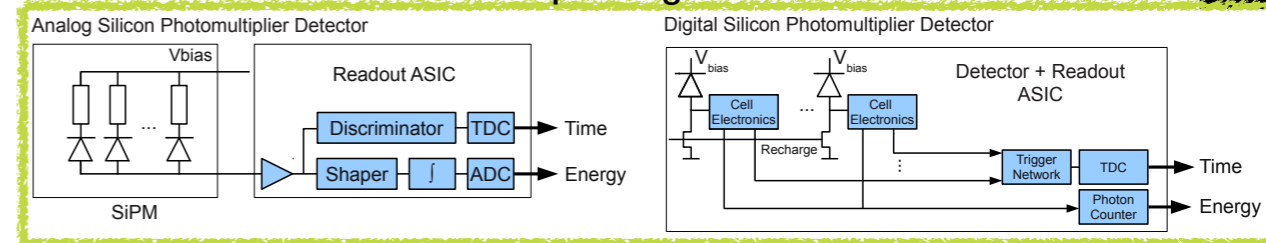
- G-APD arrays with integrated electronics
- Features
 - Counting # of fired cells
 - Time stamp of first fired cell (per die)
 - Cell-by-cell active control → disable hot cell
 - Active quenching



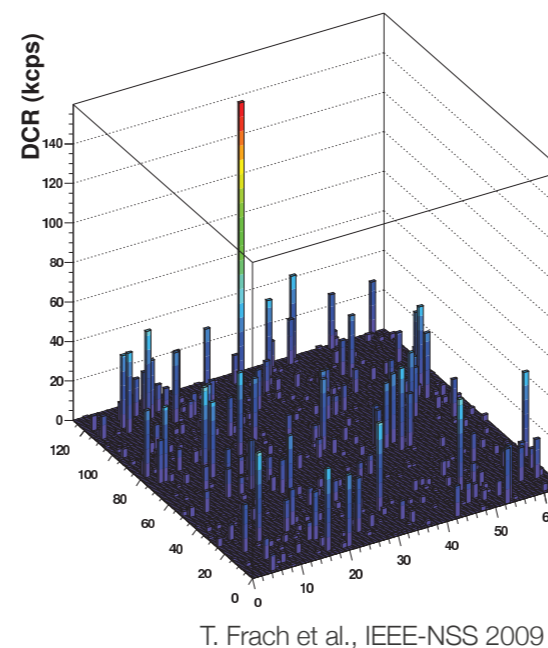
Philips digital SiPM
DPC6400-22-44 (DPC3200-22-44)

| | |
|--------------------------|-----------------------------|
| Outer dimensions | 32.6×32.6 mm ² |
| Pixel pitch | 4×4 mm ² |
| Pixel active area | 3.9×3.2 mm ² |
| # of cells | 6936(3200) |
| Cell size | 59.4×32(64) mm ² |
| Pixel fill factor | 54(74) % |
| Tile fill factor | 75(55) % |
| Operational bias voltage | 27±0.5 V |

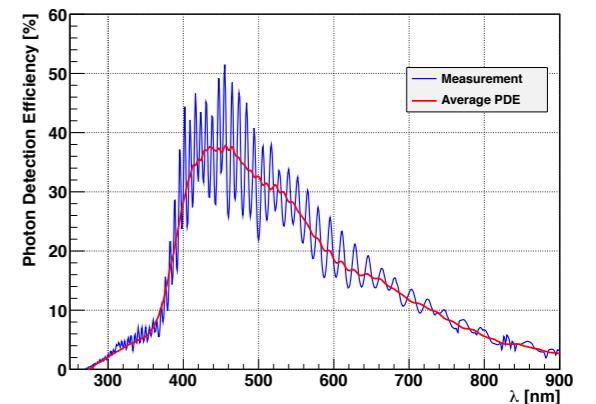
Concept of digital SiPM



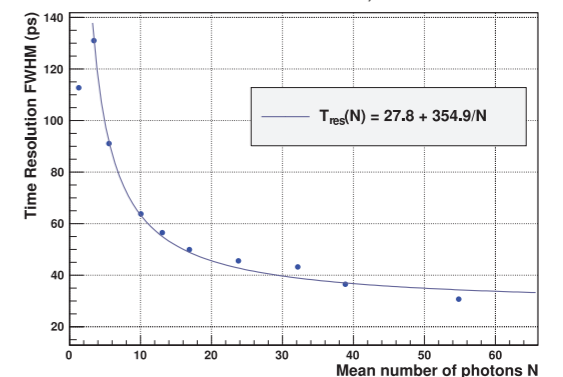
Dark noise rate distribution



Photon Detection Efficiency



Time Resolution



SiPMs with Bulk Integrated Resistor

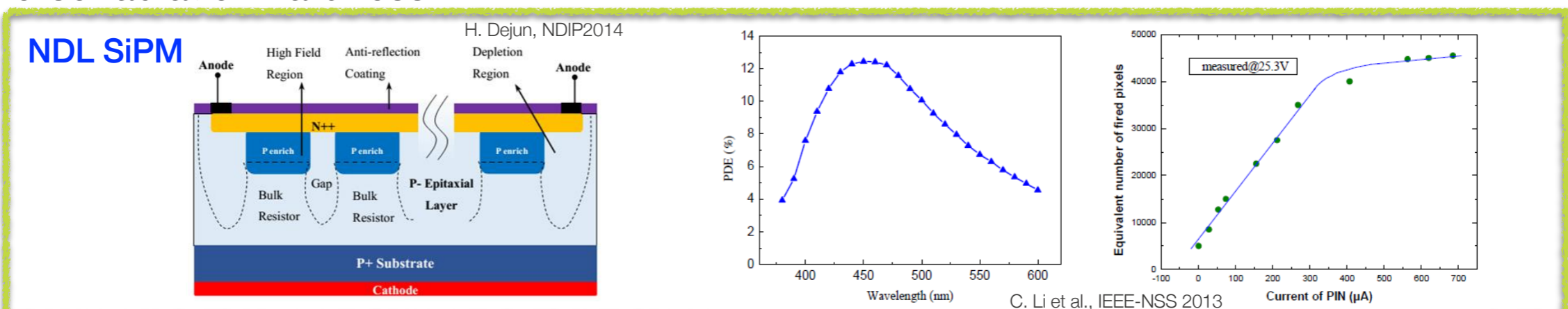
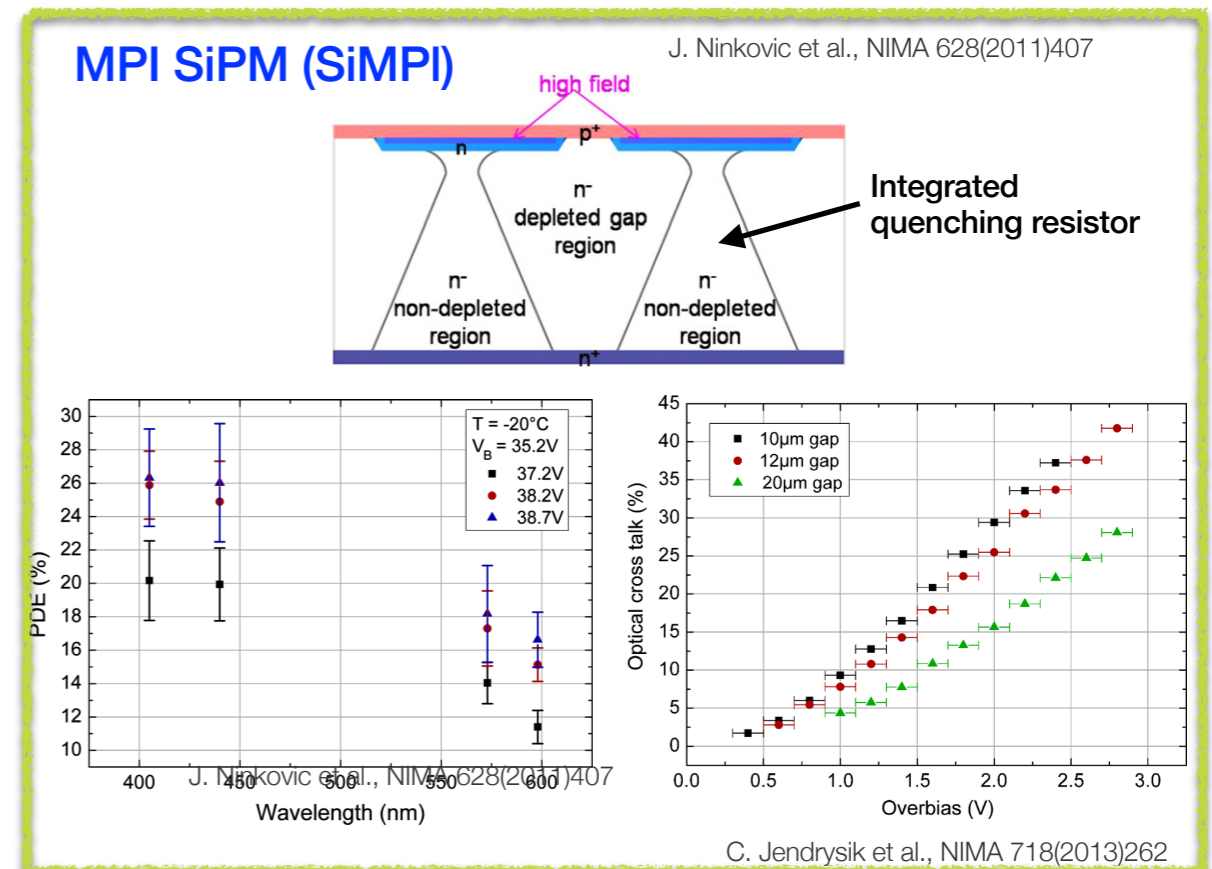
- **Quenching resistor is integrated in Si bulk.**

- **Advantages**

- High fill factor
- Simpler processing
- Flat surface → Easier implementation of anti-reflecting coating)
- Higher cell density (smaller cell)
- Less optical cross-talk

- **Issues**

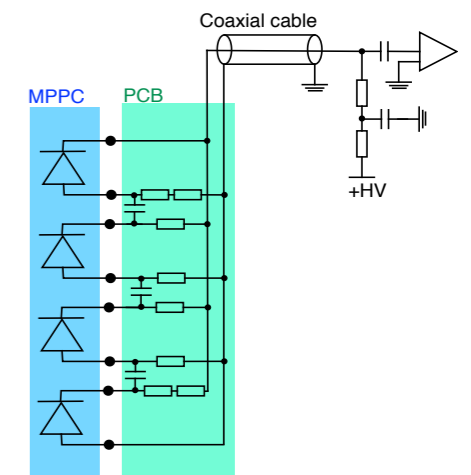
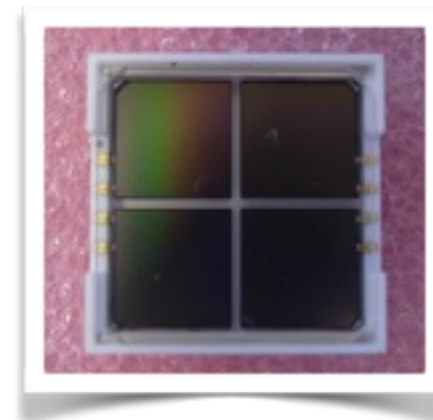
- Need thicker wafer for vertical R length
- Long recovery time
- Worse radiation hardness?



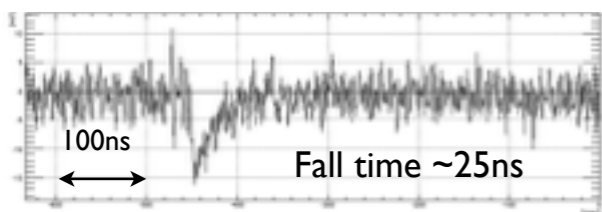
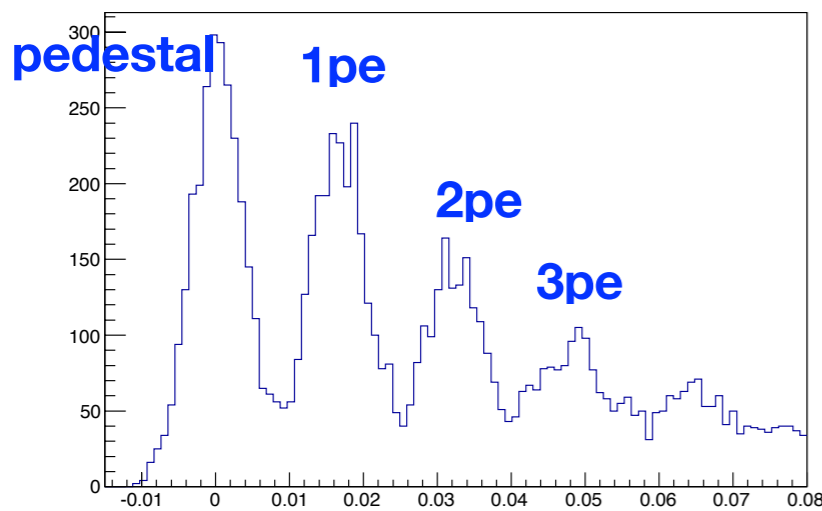
SiPM for Deep UV Light

- **DUV-sensitive MPPC developed for MEG II LXe detector**

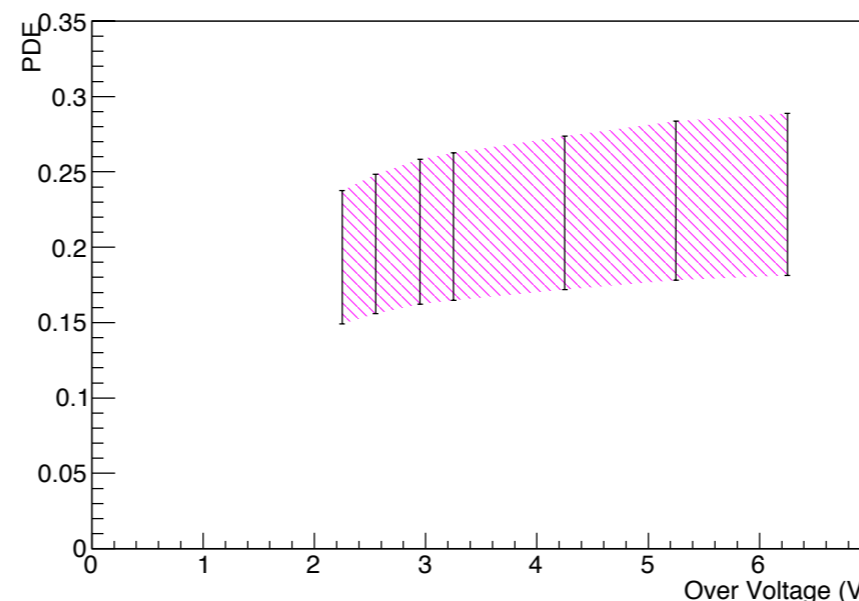
- Hamamatsu MPPC S10943-4372
- $PDE \geq 20\%$ at $\lambda=175\text{nm}$
- $12 \times 12\text{mm}^2$ (discrete array of four $6 \times 6\text{mm}^2$ chip)
- $50\mu\text{m}$ cell pitch
- Metal quench resistor
- Suppression of after-pulsing/cross-talk
- Operational at LXe temp. (165K)



Four segment chips connected in series on readout PCB

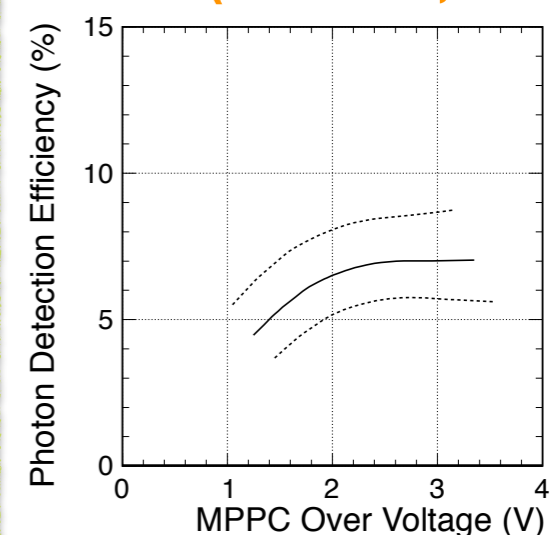


PDE vs Over Voltage



WO et al., NIMA 787(2015)220

Same technology applied for LAr ($\lambda=128\text{nm}$, $T=87\text{K}$)

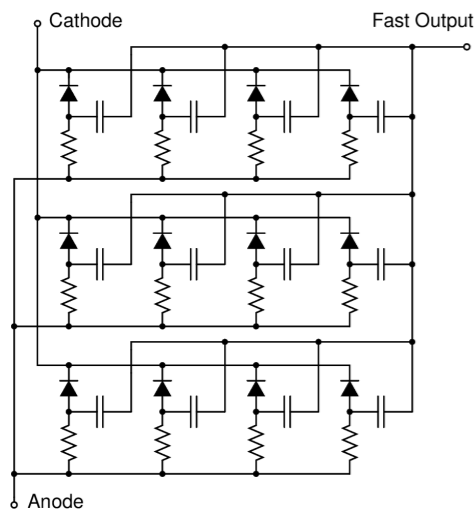


T. Igarashi et al., arXiv:1505.00091

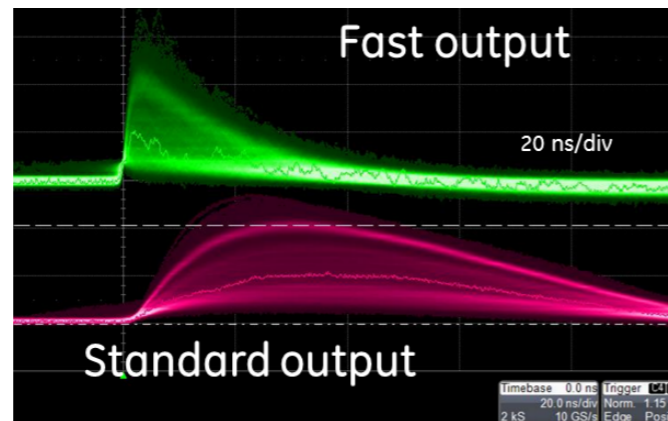
Other New Developments

- New implementation in SensL SiPM for fast timing
- Separate fast output in addition to standard output

“Fast output” scheme in SensL SiPM



Pulse shape for SensL SiPM with fast output coupled to LYSO



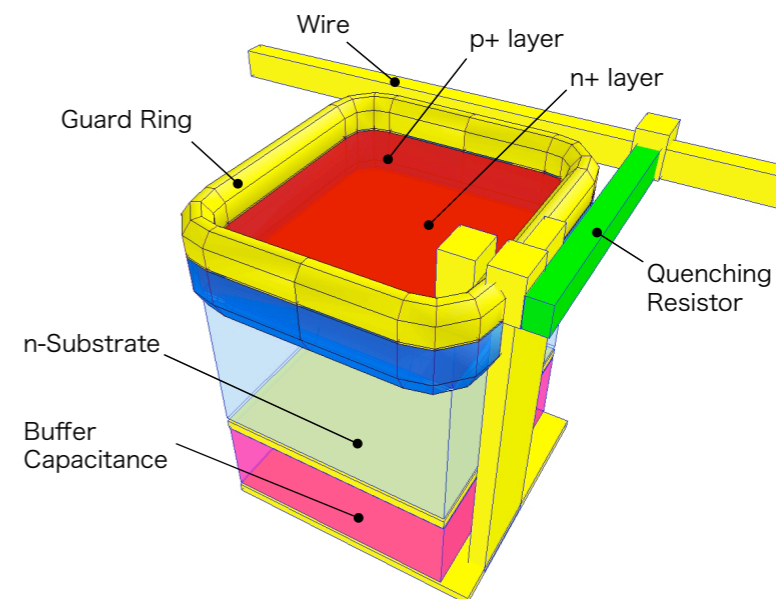
S. Dolinsky et al., IEEE-NSS 2013

A proposal for new SiPM structure

H. Oide et al., TIPP09

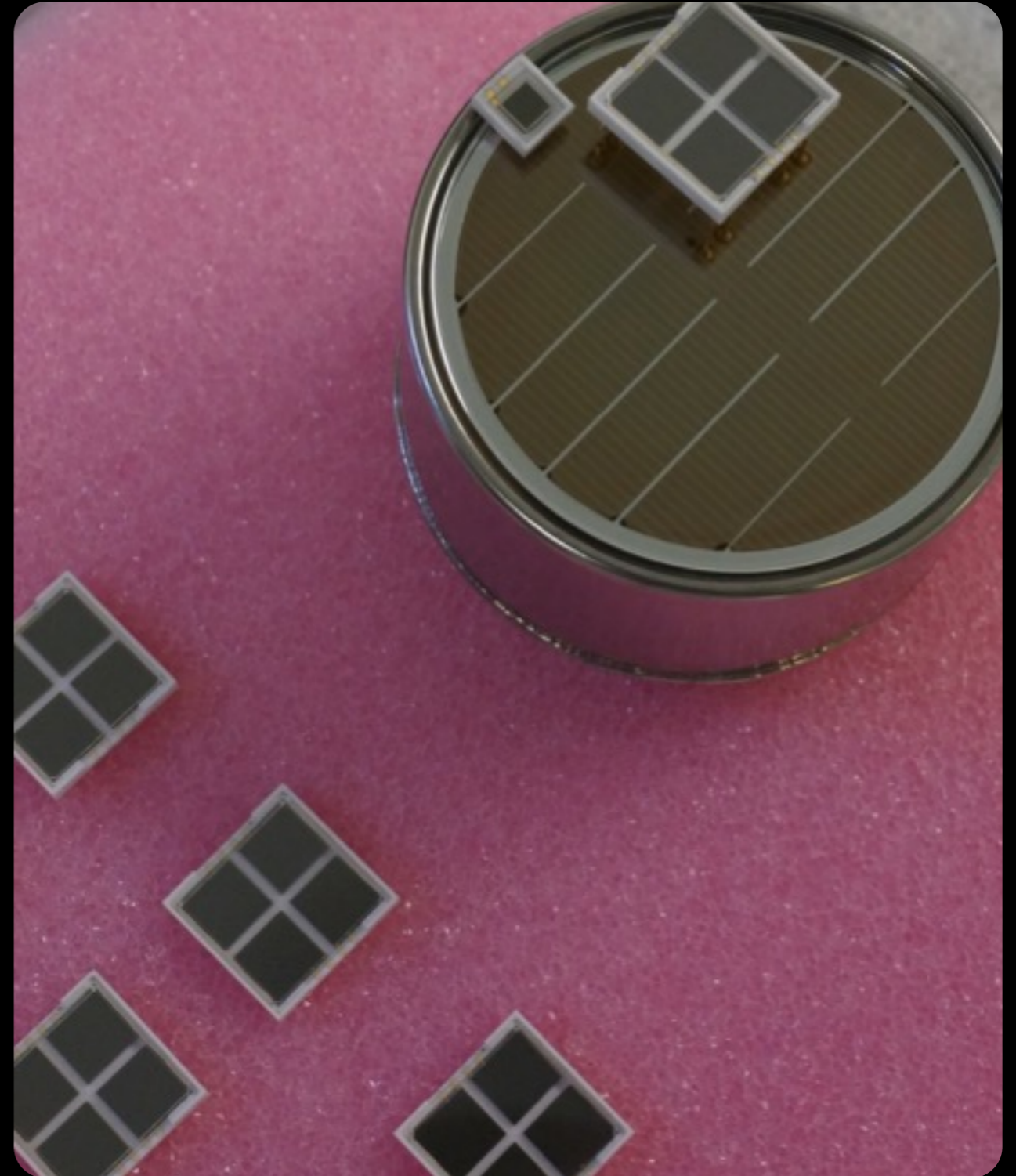
- Thinning depletion layer
 - Additional buffer capacitance parallel to p-n junction
-
- Reduced dark noise and afterpulse
 - Better radiation hardness
 - Higher gain

$$G = (C_{\text{diode}} + C_{\text{buffer}}) \Delta V / e$$



Contents

- Introduction
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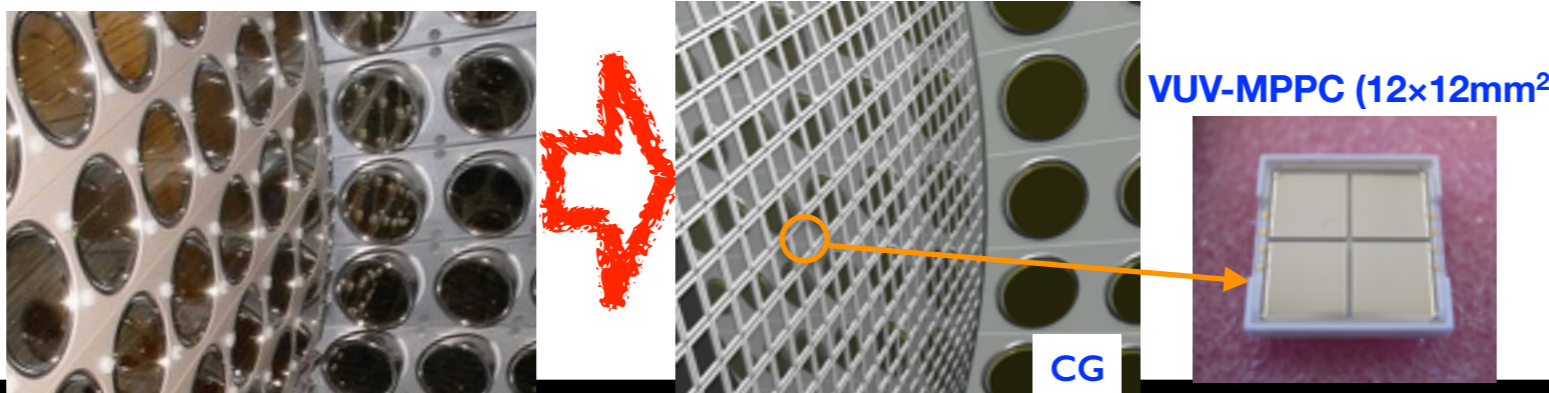
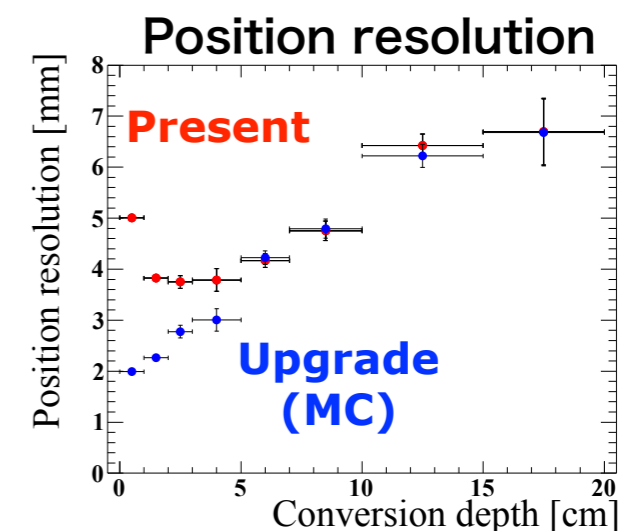
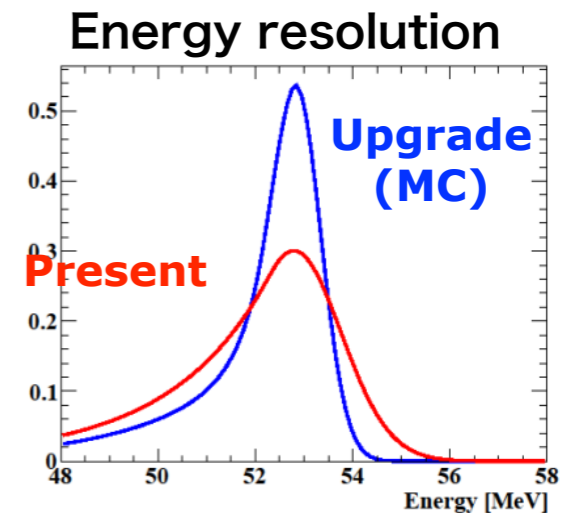
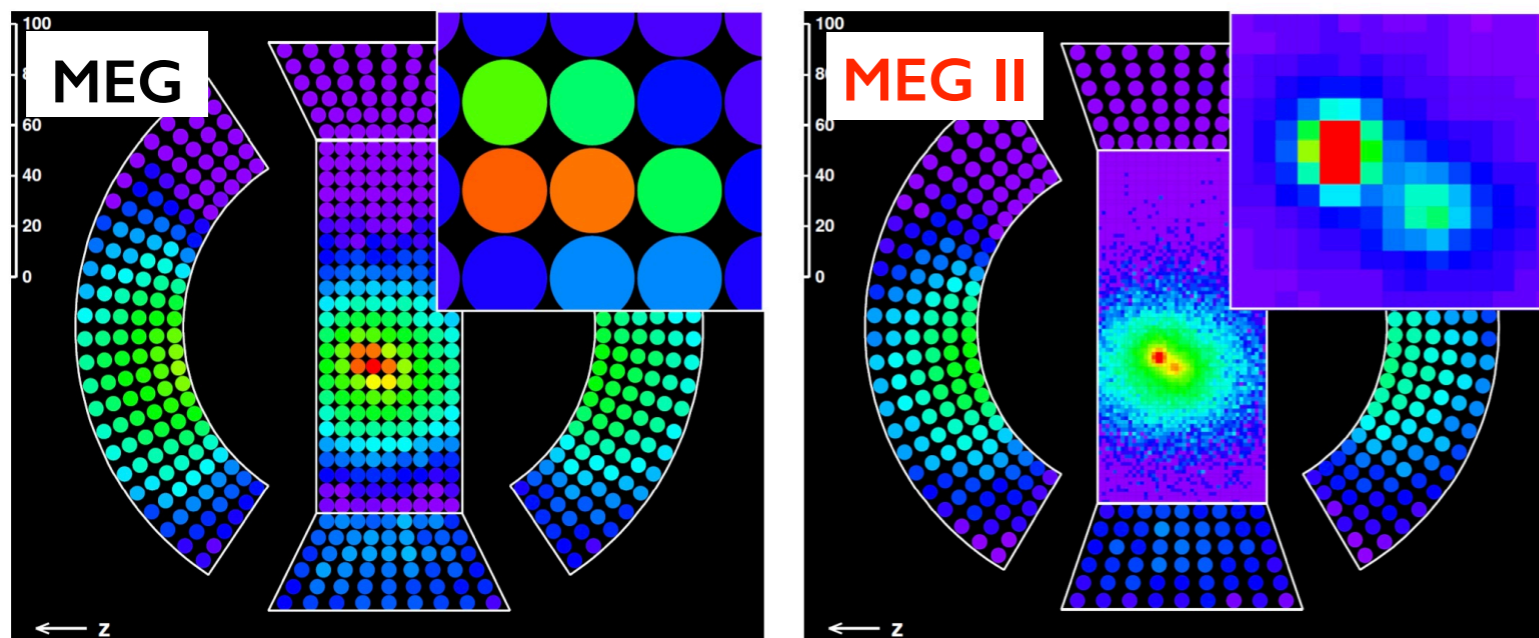


MEG II LXe Detector

- Upgrade for LXe Detector in MEG experiment to measure 52.8MeV γ -ray from $\mu \rightarrow e\gamma$ decay
- Highly granular scintillation readout with VUV-MPPC
 - 256 PMTs (2 inch) replaced with 4092 VUV-MPPCs ($12 \times 12 \text{mm}^2$)
- Construction to be finished within 2015

MEG II Proposal: arXiv:1301.7225

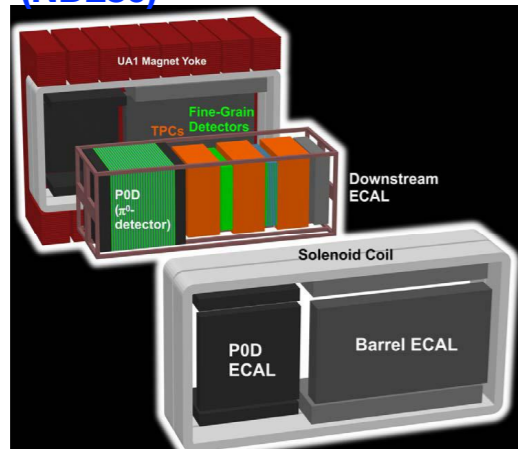
WO et al., NIMA 787(2015)220



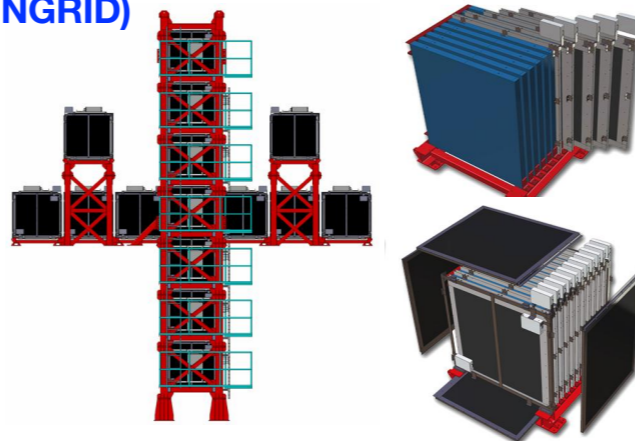
T2K: Neutrino Oscillation Experiment

- A large number of MPPCs totalling ~56,000 used in several detectors in T2K.
- Working fine for several years
- # of bad channel < 0.28% incl. problem of readout electronics

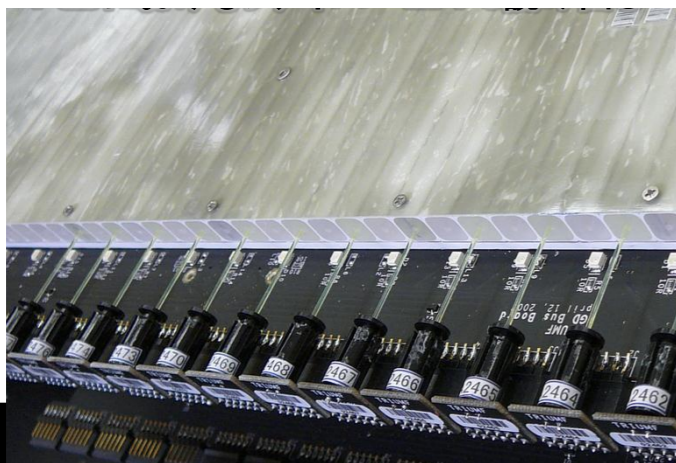
T2K off-axis near detectors (ND280)



T2K on-axis near detectors (INGRID)



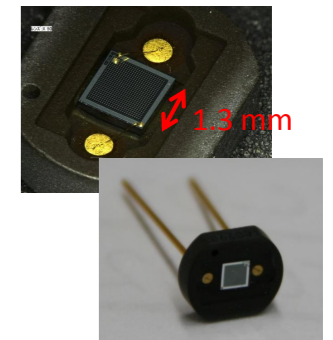
MPPC readout (FGD)



A. Minamino, Next generation photosensor worksp 2010

| Item | Spec |
|--|--|
| Active area | 1.3 x 1.3 mm ² |
| Pixel size | 50 x 50 μm ² |
| Num. of pixels | 667 |
| Operation voltage | 70 V (typical) |
| PDE @ 550nm | ~ 25 % |
| Dark count (Gain = 7.5 x 10 ⁵) | < 1.35 Mcps @ 25 deg. (Thre. = 0.5 p.e.) |
| Num. of device | 56,000 |

S10362-13-050C
Developed for T2K



Produced by Hamamatsu Photonics

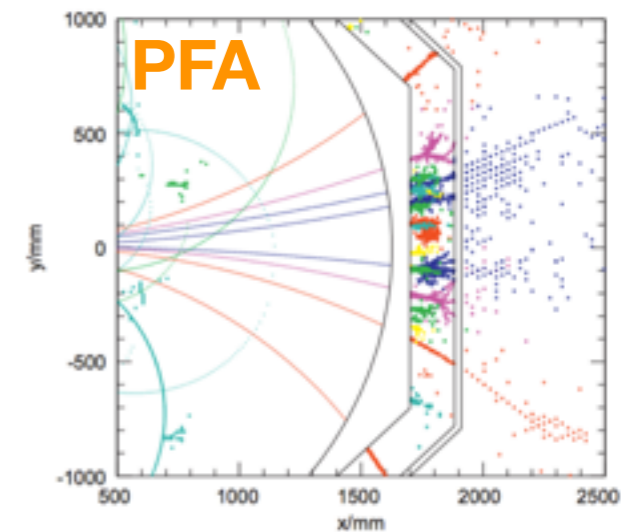
17

T. Kikawa, Next generation photosensor worksp 2012

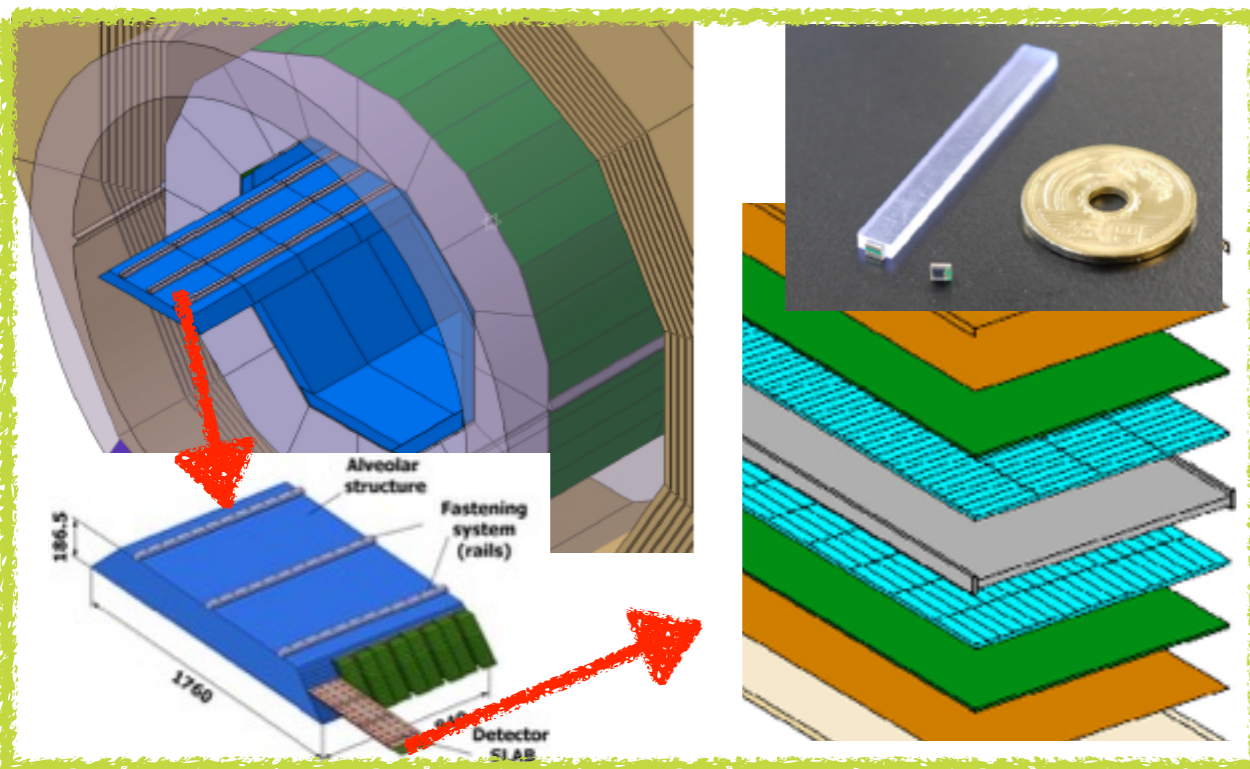
| Detector | # of ch | # of bad ch | | Fraction of bad ch | |
|----------|---------|-------------|------|--------------------|-------|
| | | 2010 | 2012 | 2010 | 2012 |
| INGRID | 10796 | 18 | 37 | 0.17% | 0.34% |
| FGD | 8448 | 20 | 20 | 0.24% | 0.24% |
| ECAL | 22336 | 35 | 58 | 0.16% | 0.26% |
| P0D | 10400 | 7 | 28 | 0.07% | 0.27% |
| SMRD | 4016 | 7 | 15 | 0.17% | 0.37% |
| 計 | 55996 | 87 | 158 | 0.16% | 0.28% |

ILD Scintillator Calorimeters

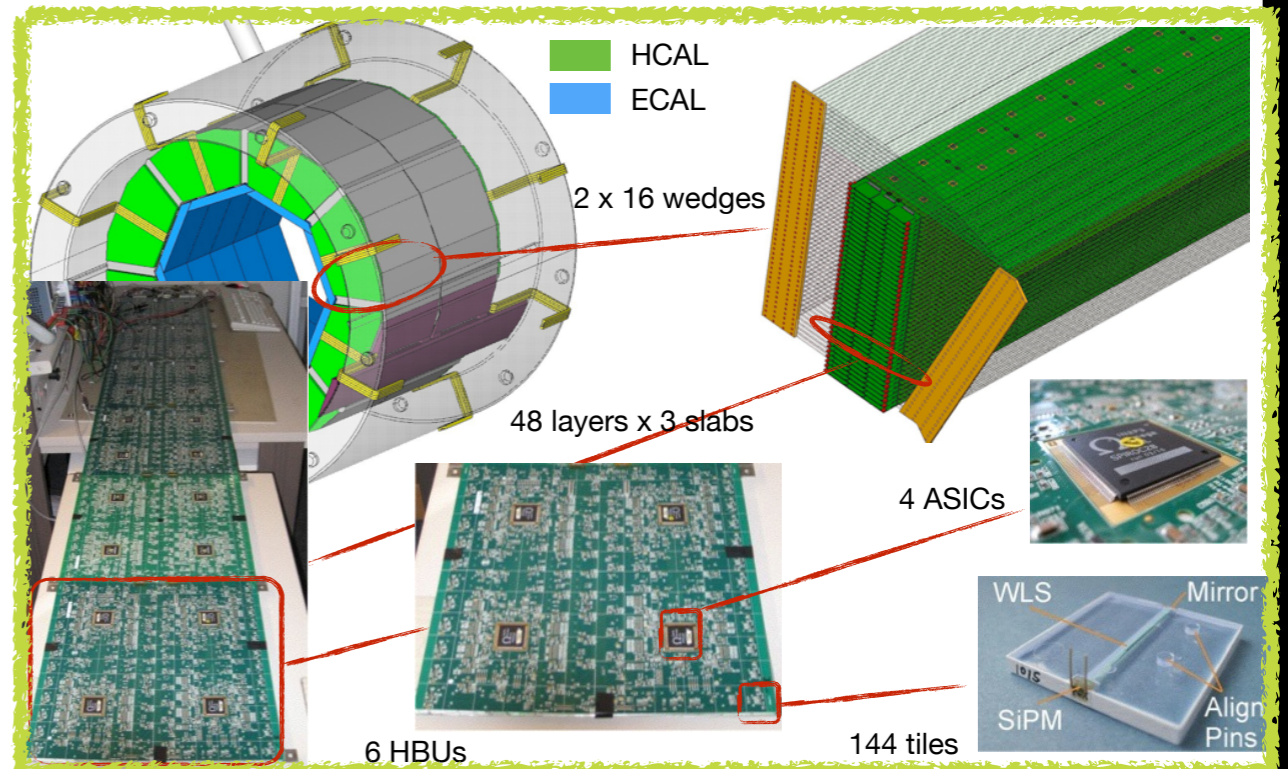
- Highly granular calorimeter for ILC detector based on Particle Flow Algorithm (PFA).
 - AHCAL: $\sim 10^7 \times (30 \times 30 \times 3 \text{ mm}^2 \text{ scinti. cell} + \text{SiPM})$
 - ScECAL: $\sim 10^7 \times (5 \times 45 \times 2 \text{ mm}^2 \text{ scinti. strip} + \text{SiPM})$
- SiPM technology allows
 - SiPM and readout electronics are integrated in active volume
 - Calorimeters in solenoid field of 4T



ScECAL



AHCAL

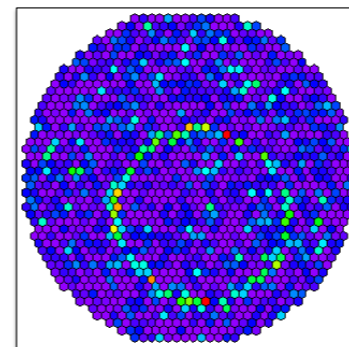
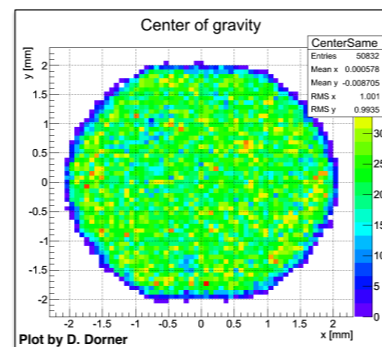
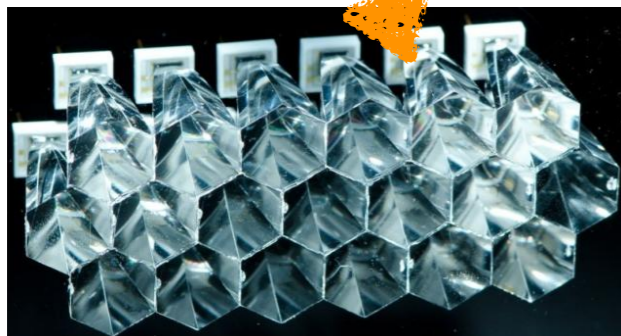
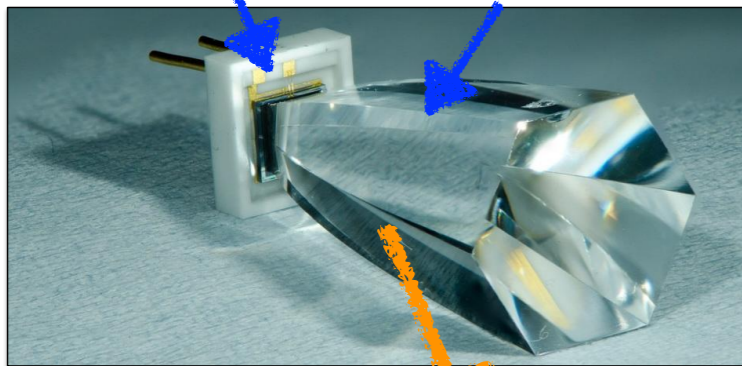


FACT: First G-APD Cherenkov Telescope

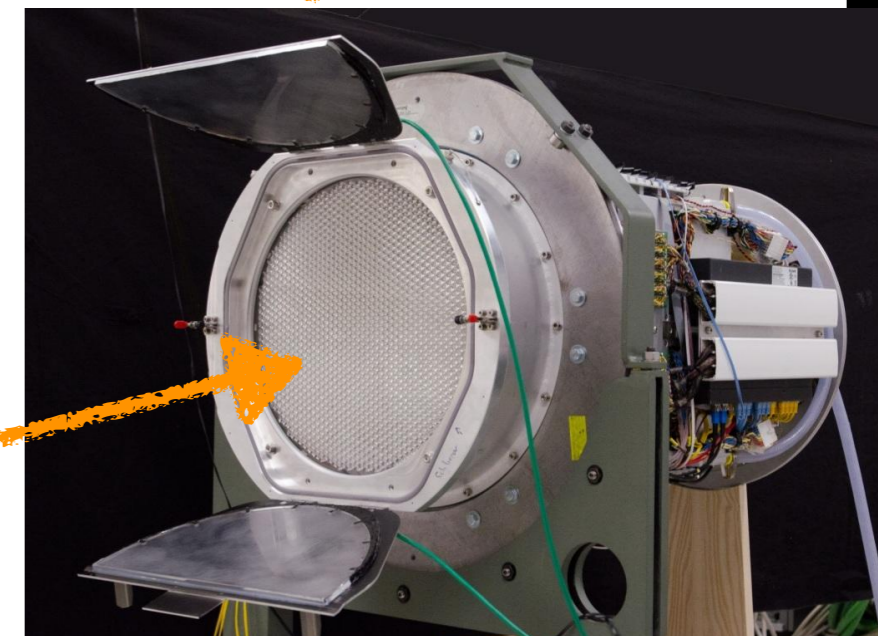
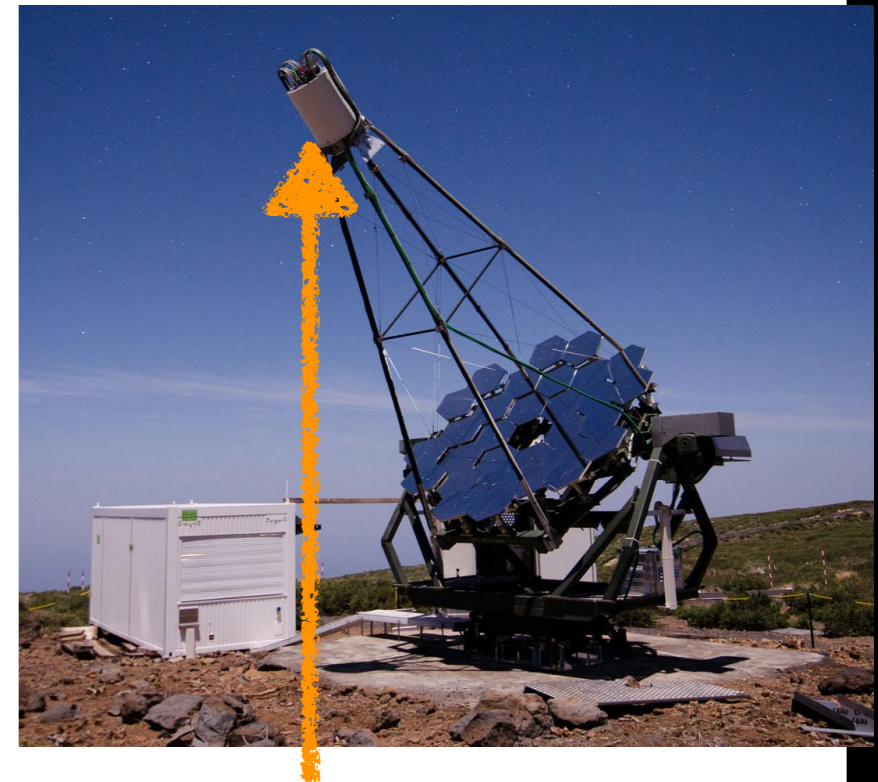
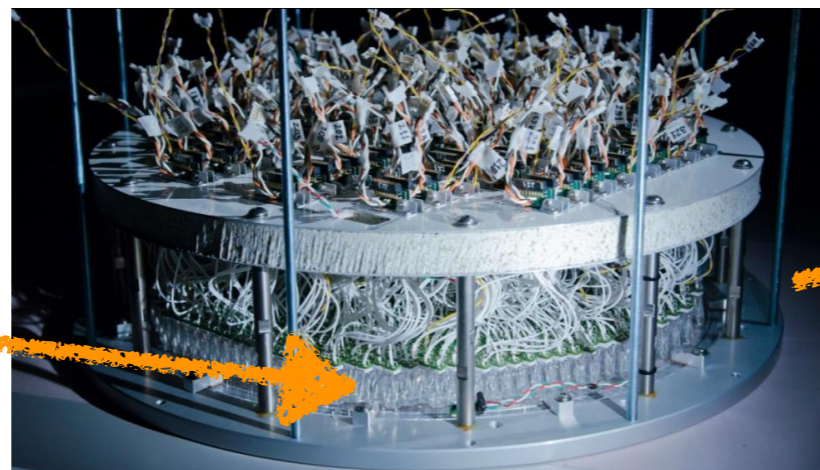
- SiPM-based camera for Imaging Atmospheric Cherenkov Telescopes (IACTs)
- 1440 pixel modules based on MPPC with light collecting cone.
- Integrated electronics: trigger and digitisation (DRS4 chip)
- First operation on Oct. 11, 2011 (full moon)

MPPC S10362-33-050C

Light collecting cone
(injection moulded PMMA)



1440 pixels glued onto front window



Th. Krähenbühl, Photodet2012

Summary

- Vast progress in development of SiPM technology since last two decades.
- SiPM technology is mature enough in terms of both performance and cost to be employed in many projects.
- Many advantages, while some weak points to be overcome.
 - Dark noise
 - Correlated noise
 - Saturation
 - Radiation hardness
 - Temperature dependence
 - Limited sensor area
- Many new developments and new applications are on-going.

Summary

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Summary

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Thank you for your attention!

Questions?

More complete reviews

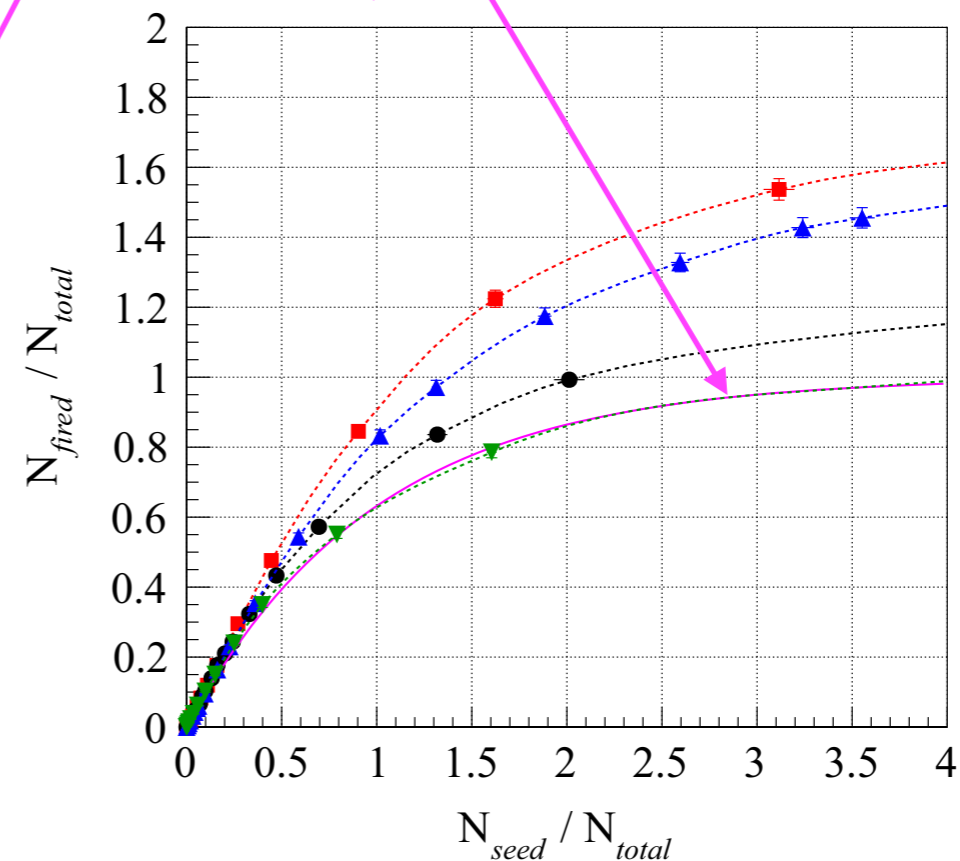
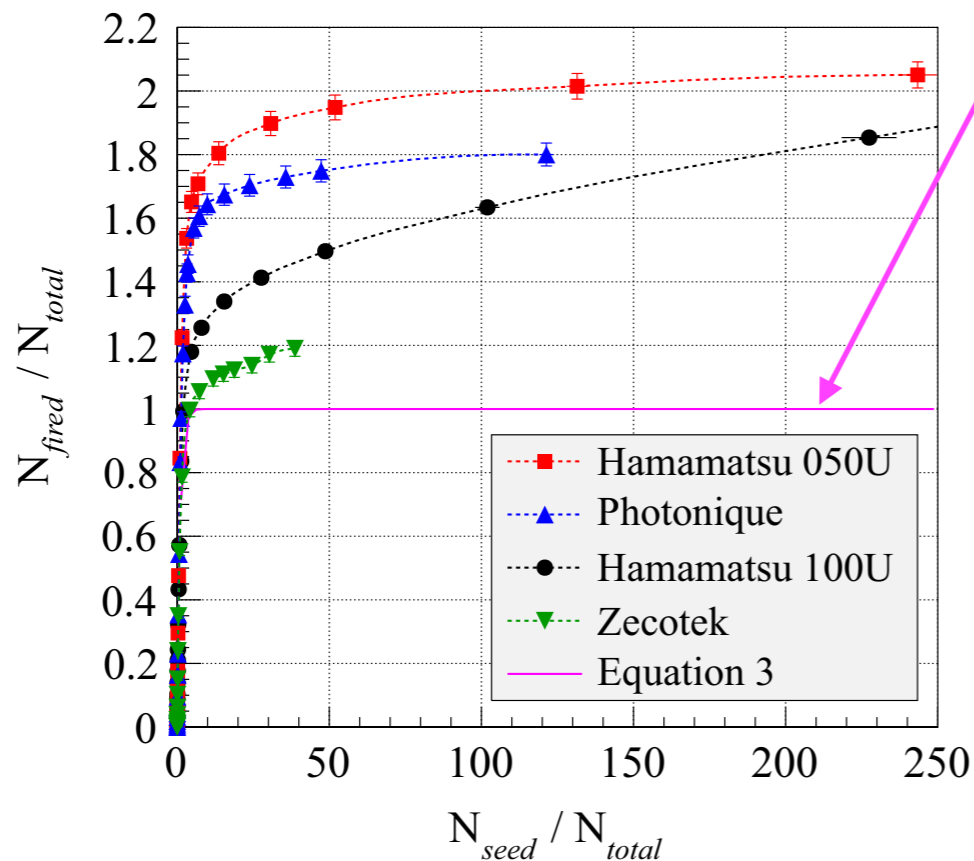
- V. Puill, *“Tutorial SiPM”*, NDIP2014
- G. Collazuol, *“Status and Perspectives of Solid State Photo-detector”*, RICH2013

Backup

Over-Saturation?

- Some reports on over-saturation
 - $N_{\text{fired}} > N_{\text{cell}}$ with fast laser (32ps pulse width \rightarrow No chance of cell recovery)
- Still to be understood

$$N_{\text{fired}} = N_{\text{cell}} \left(1 - e^{-\frac{N_{\text{photon}} PDE}{N_{\text{cell}}}} \right)$$

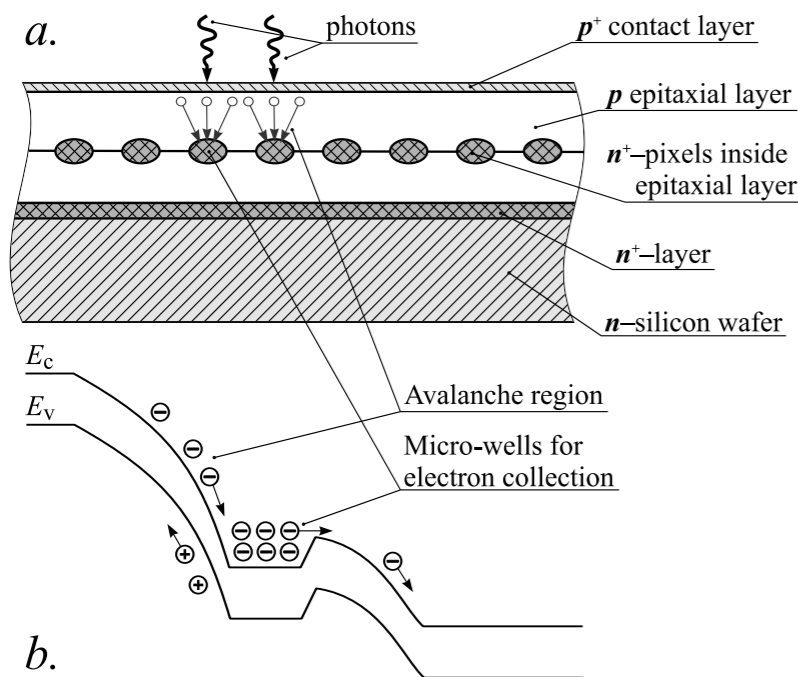


L. Gruber et al. NIMA737 (2014) 11

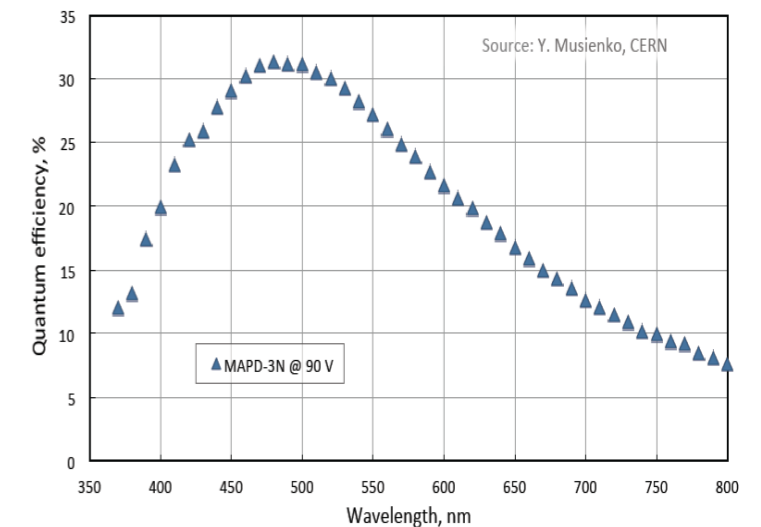
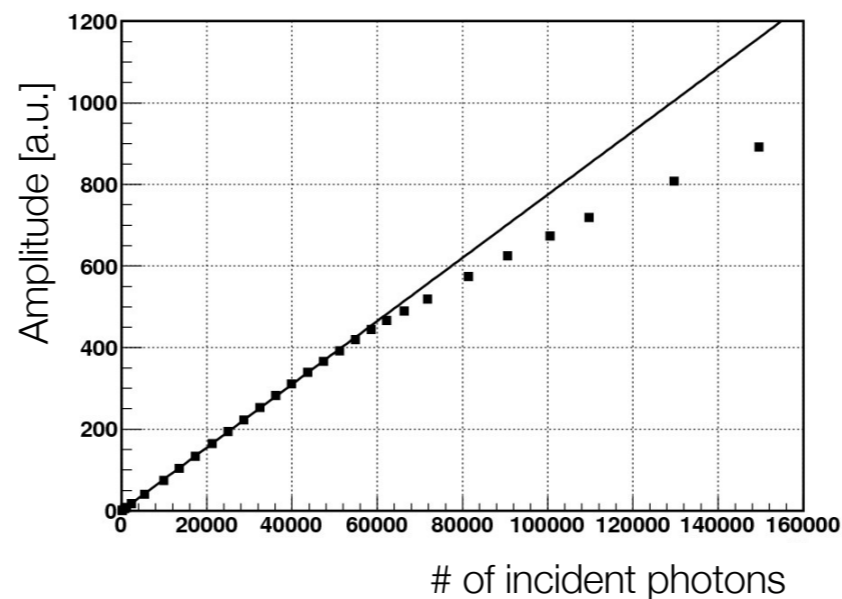
Even Smaller... Micro Cell SiPM

- **Micro-pixel APD (MAPD) from Zecotek**

- Cells inside epitaxial layer
- No quenching resistor. Directly biased p-n junction under each cell is used to quench avalanche instead.
- up to 40,000 cells/mm²



135000 cells (3x3mm²)
= 15000 cells/mm²



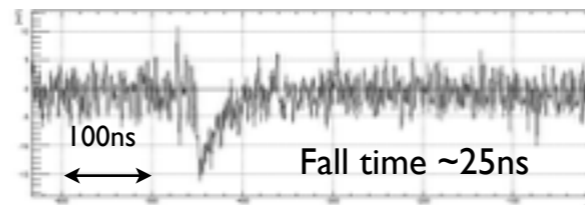
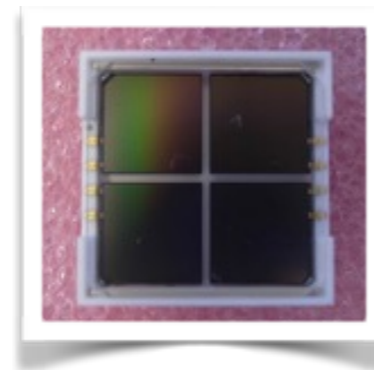
Measured by Y. Musienko (CERN)

Z.Sadygov, et al., Tech. Phys. Lett. 36(2010)528

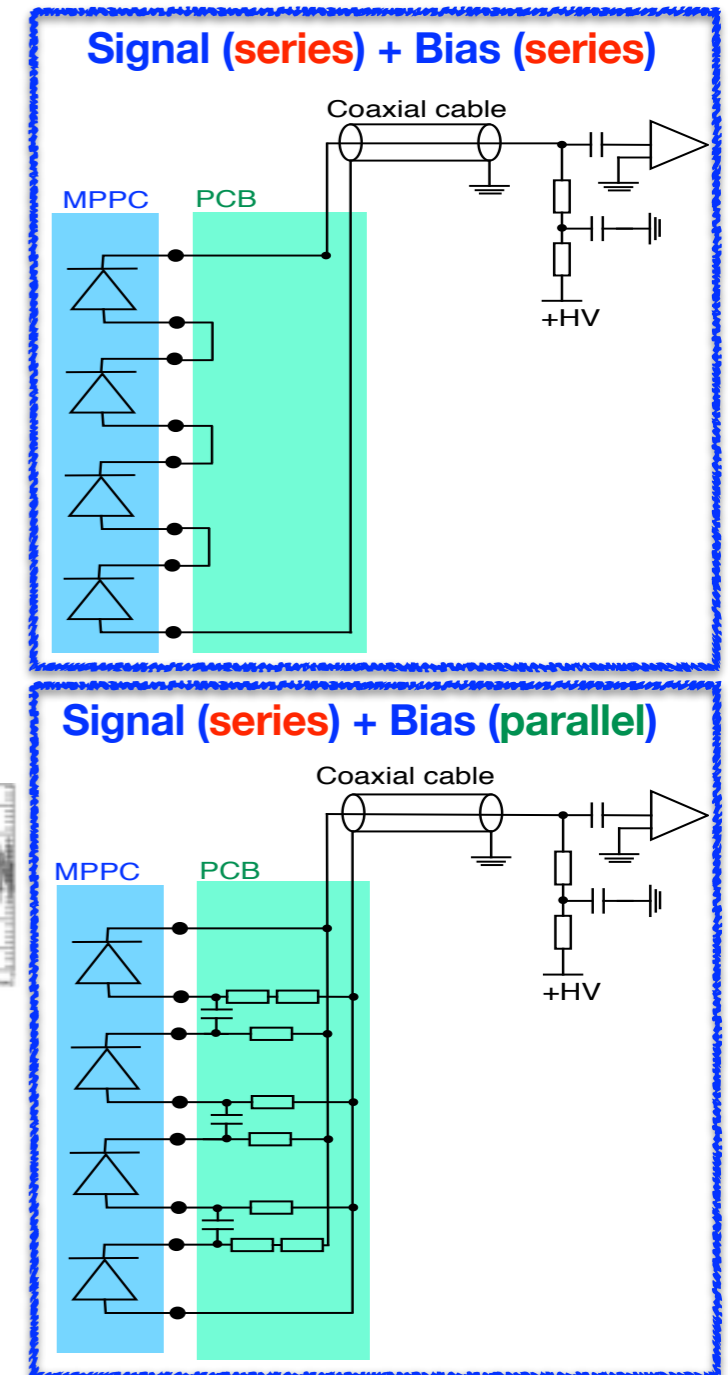
Large Area Sensor

- SiPM sensor area is limited by dark noise and sensor capacitance.
- Cost per unit area is already comparable to PMT!
- Solutions for large area sensor
 - Array
 - Discrete or monolithic
 - Need individual channel readout
 - Series connection of multiple sensors
 - Working as a single sensor → Reduction of # of readout channel
 - Reduced sensor capacitance
 - Need operation at low temp to reduce dark noise

Hamamatsu VUV-MPPC
(total area $12 \times 12 \text{mm}^2$,
four segments)



Series connection of SiPM segments



WO et al., NDIP2014

MEG II Pixelated Scintillator Detector

- Timing counter for 52.8MeV positron from $\mu \rightarrow e\gamma$ decay in MEG II
- $\times 512$ fast scintillator plates, each of which is readout by multiple SiPMs connected in series
- Excellent timing resolution of 30-40ps demonstrated with prototype
- To be constructed in 2015

MEG II Proposal: arXiv:1301.7225
 WO, NIMA 732(2013)146
 M. De Gerone, WO et al. JINST9(2014)C02035
 P. W. Cattaneo, WO et al., IEEE-TNS 61(2014)2657

Single counter

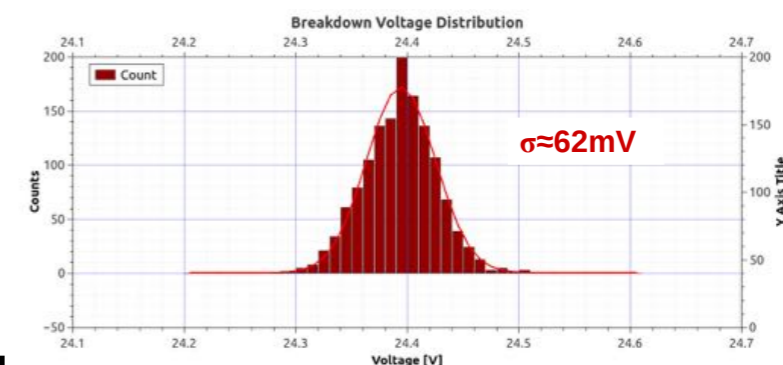
MEG timing counter

MEG II timing counter
 ($\times 512$ counter modules)



6 SiPMs connected in series
 (AdvanSiD AMSASD-NUV3S-P50, 3x3mm², 50 μ m)

V_{bd} distribution for ~ 4000 SiPMs



Plastic scintillator bar
 (40x40x900mm³) + PMT

